

TA-202:MANUFACTURING PROCESSES

# ADVANCED MACHINING PROCESSES: AN INTRODUCTION

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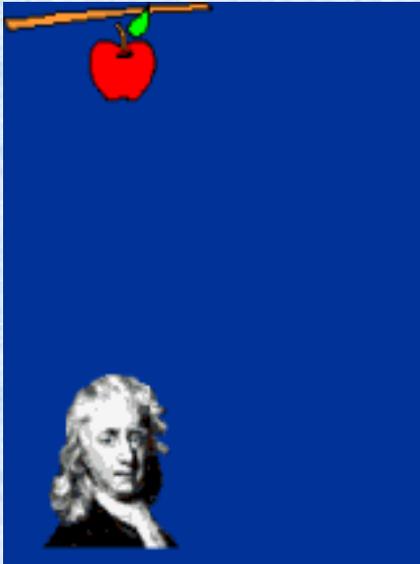
**\* BE KEEN OBSERVER**

EXAMPLES OF SOME SCIENTISTS



SIR ISSAC NEWTON

KEEN OBSERVATIONS HAD LED TO BIG INVENTIONS



WHY IT FELL DOWNWARD?  
WHY DID IT NOT GO UP?



THEORY OF GRAVITATION



DR. C. V. RAMAN



OBSERVING THE WAVES IN SEA  
WHILE GOING ABROAD

WHY THE WATER OF  
SEA LOOKS BLUE IN  
COLOUR?

LED TO THE INVENTION OF  
“*RAMAN EFFECTS*”

**NOBLE PRIZE  
WINNER**

# IS IT NECESSARY FOR THE TOOL TO BE HARDER THAN WORKPIECE

?

HOW A ROPE CAN WEAR THE PULLEY ?



WORN OUT PULLEY BY A ROPE

# INTRODUCTION

# ENGINEERING MATERIALS

METALS AND ALLOYS

PLASTICS AND COMPOSITES

CERAMICS

- GETTING MORE POPULARITY
- DEFINITE ADVANTAGES OVER OTHERS

HOW TO  
MACHINE  
THEM  
?

SOLUTION

## ADVANCED MACHINING PROCESSES

# PRESENT DAY DEMAND TRENDS IN INDUSTRIES (AEROSPACE , MISSILES , AUTOMOBILES, NUCLEAR REACTORS, ETC.)



**WORK PIECE MATERIAL HARDNESS >> TOOL MATERIAL HARDNESS**

**HOW TO SOLVE THE PROBLEM**



**ADVANCED MACHINING PROCESSES**

**WORKPIECE HARDNESS DOES NOT MATTER IN AMPs**

WHY DO YOU  
NEED ADVANCED  
MACHINING  
PROCESSES  
(AMPs)

?

- **LIMITATIONS OF CONVENTIONAL MACHINING METHODS**  
(WORKPIECE HARDNESS, SURFACE ROUGHNESS, 3-D PARTS,  
COMPLEX GEOMETRIES)
- **INCREASED WORKPIECE HARDNESS → DECREASED ECONOMIC  
CUTTING SPEED → LOWER PRODUCTIVITY**
- **RAPID IMPROVEMENTS IN THE PROPERTIES OF MATERIALS**  
(WORKPIECE → HARDNESS, STRENGTH, ETC.)
- **METALS & NON – METALS : STAINLESS STEEL , HIGH STRENGTH  
TEMPERATURE RESISTANT (HSRT) SUPER ALLOYS: STELLITE, ETC.**
- **TOOL MATERIAL HARDNESS >> WORKPIECE HARDNESS**
- **REQUIRES MUCH SUPERIOR QUALITY OF TOOL  
MATERIALS**

WHY DO YOU  
NEED ADVANCED  
MACHINING  
PROCESSES  
(AMPs)

?

## PRODUCT REQUIREMENTS

- COMPLEX SHAPES
- MACHINING IN INACCESSIBLE AREAS
  - LOW TOLERANCES (SAY, 10  $\mu\text{m}$ )
- BETTER SURFACE INTEGRITY (NO SURFACE DEFECTS, ETC.)
- HIGH SURFACE FINISH (NANO LEVEL Ra VALUE =>nm)
- MINIATURIZATION OF PRODUCTS (EXAMPLES: LANDLINE PHONE & MOBILE, OLD COMPUTERS & LAP TOP, ETC.)
  - HIGH MRR

**WHY DO YOU  
NEED ADVANCED  
MACHINING  
PROCESSES**

**?**

**HIGH PRODUCTION RATE WHILE PROCESSING DIFFICULT –TO-  
MACHINE MATERIALS**

**LOW COST OF PRODUCTION**

**PRECISION AND ULTRAPRECISION MACHINING**

**(NANO-METER MACHINING)**



**REQUIRES MATERIAL REMOVAL IN THE FORM OF ATOMS AND / OR  
MOLECULES**



**ADVANCED MACHINING PROCESSES**

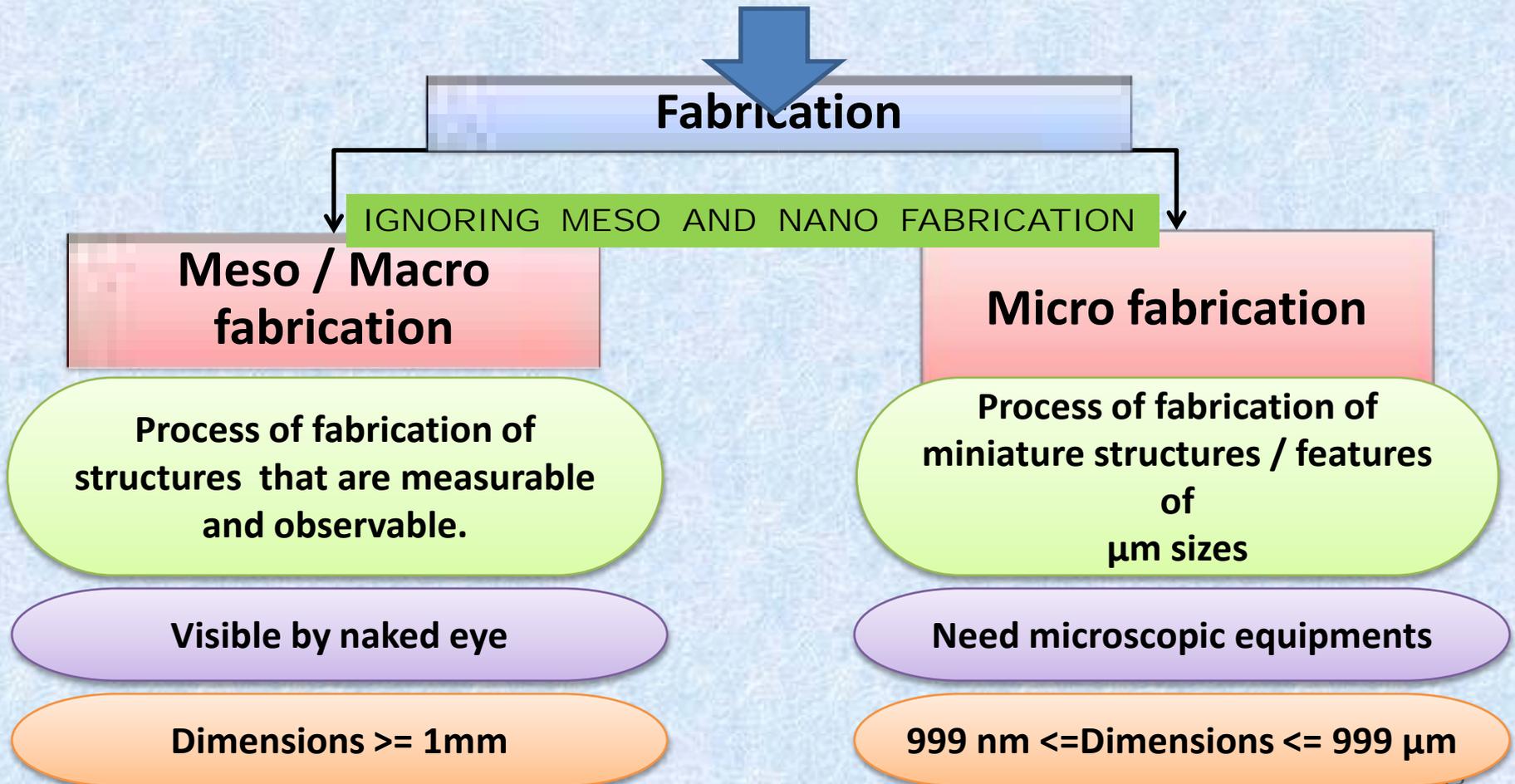
**(AMPs)**

**WHY DO YOU  
NEED ADVANCED  
MACHINING  
PROCESSES ?**

**some examples**

# Fabrication

Building of machines, structures, or process equipment by cutting, shaping and assembling components made from raw materials.



- CLASSIFICATION BASED ON THE **KIND OF ENERGY USED** : MACHANICAL, THERMOELECTRIC, ELECTROCHEMICAL & CHEMICAL, BIOCHEMICAL

## MECHANICAL

### MACHINING

ABRASIVE JET MACHINING (AJM)

ULTRASONIC MACHINING (USM)

WATER JET MACHINING  
(WJM)

ABRASIVE WATER JET MACHINING  
(A WJM)

### FINISHING

ABRASIVE FLOW FINISHING (AFM)

MAGNETIC ABRASIVE FINISHING  
(MAF)

MAGNETORHEOLOGICAL  
FINISHING (MRF)

## THERMOELECTRIC

PLASMA ARC MACHINING (PAM)

LASER BEAM MACHINING (LBM)

ELECTRON BEAM  
MACHINING (EBM )

ELECTRIC DISCHARGE MACHINING (EDM)

ION BEAM MACHINING (IBM)

## ELECTROCHEMICAL & CHEMICAL

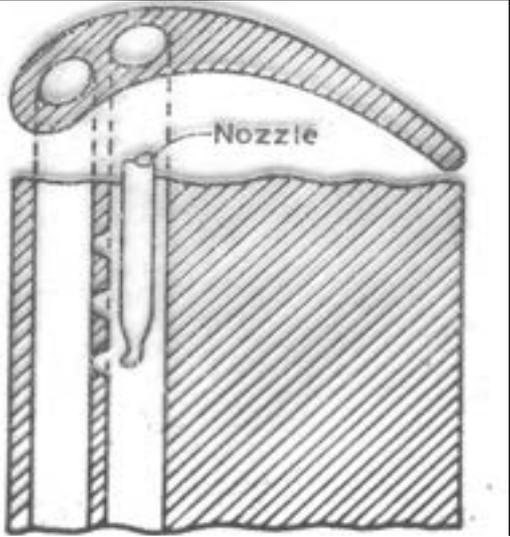
ELECTROCHEMICAL MACHINING  
(ECM)

CHEMICAL MACHINING (CHM)

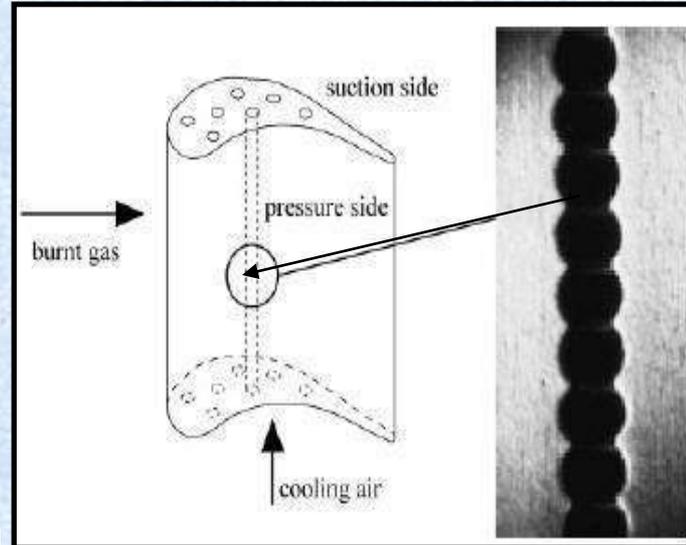
BIOCHEMICAL MACHINING (BM)

# MACHINING OF COMPLEX SHAPED WORKPIECES?

## ELECTROCHEMICAL MACHINING



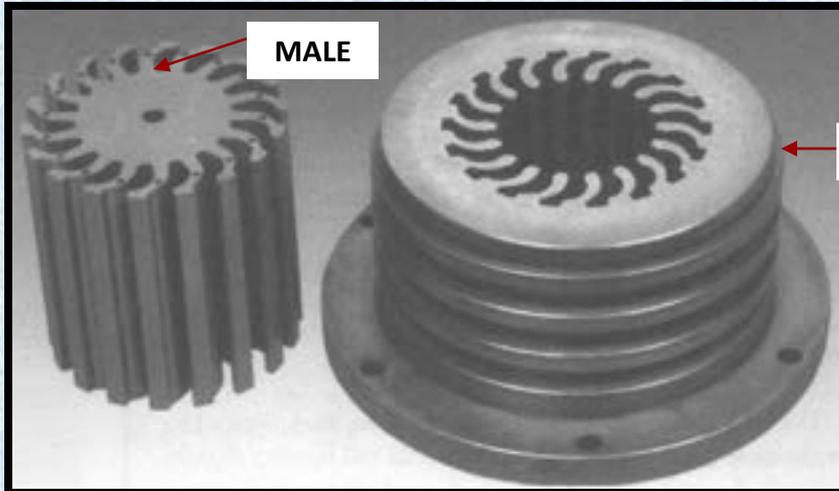
HOLE NORMAL TO THE WA I



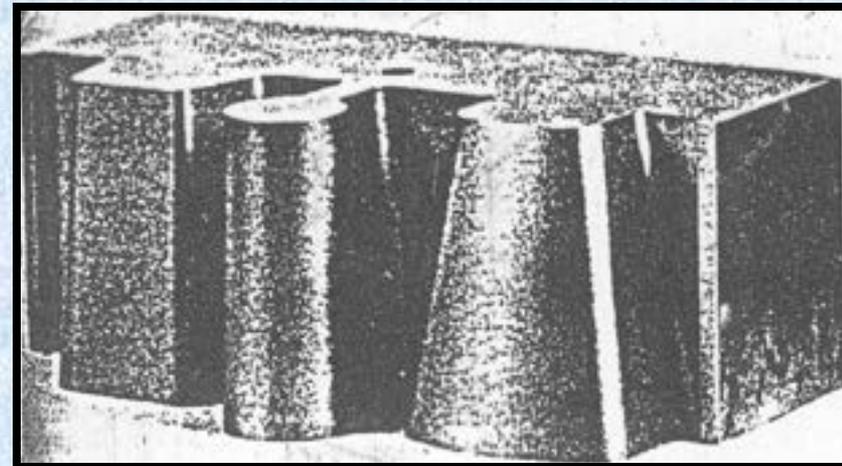
Turbine Blade with cooling Holes

EXPERIMENTAL PARAMETERS	EXPERIMENTAL PROFILE	COMPARISON WITH THEORETICAL PROFILE	PHOTOGRAPH OF MACHINED PROFILED HOLE
Experiment No:5 Voltage: 10.5V Feed rate, 6.17 mm/min Feed rate, 6.16 mm/min			

Contoured Hole Drilled In Inconel Using ECM



PRECISION WIRE EDM



TAPER 3-D CUTTING USING TRAVELING WIRE-EDM

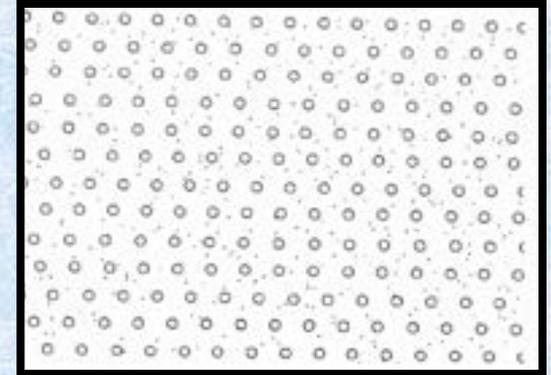
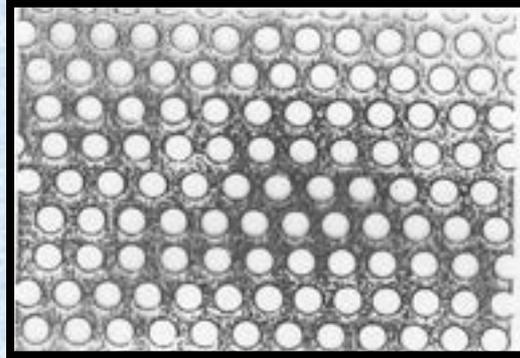
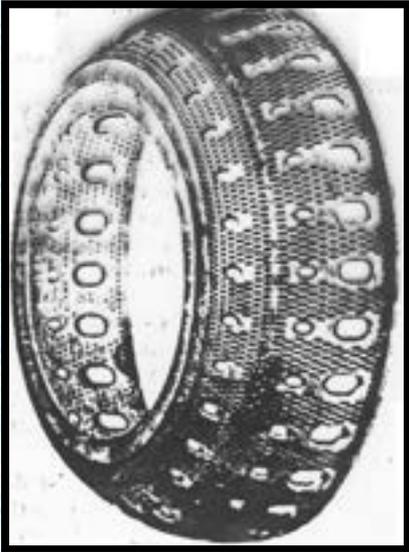
# PATTERN OF HOLES DRILLED BY EBM

**PART OF A HELICOPTER  
TURBINE “ HOLES DRILLED  
BY EBM”**

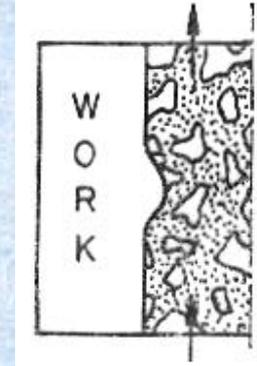
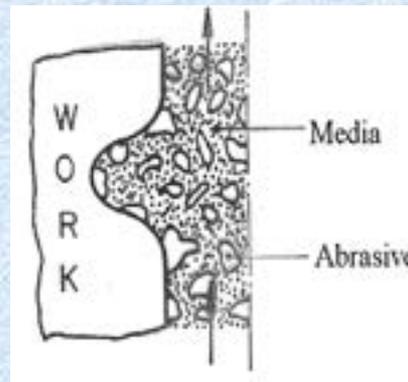
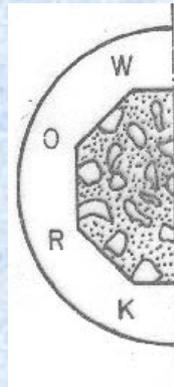
HOLE=0.09 mm $\phi$  HOLES DENSITY = 4000/cm<sup>2</sup>  
WORKPIECE- S.S.;

THICK = 0.2 MM; TIME = 10  $\mu$ S/HOLE

HOLE  $\phi$  = 0.006 mm (6  $\mu$ m);  
HOLES DENSITY = 200,000 / cm<sup>2</sup> ;  
THICKNESS = 0.12 mm; TIME = 2  $\mu$ s / HOLE



**AFF MEDIA ACTS AS A SELF-DEFORMABLE STONE**



**SOME  
IMPORTANT  
CHARACTERISTICS  
OF AMPs  
&  
MACHINE  
TOOLS**

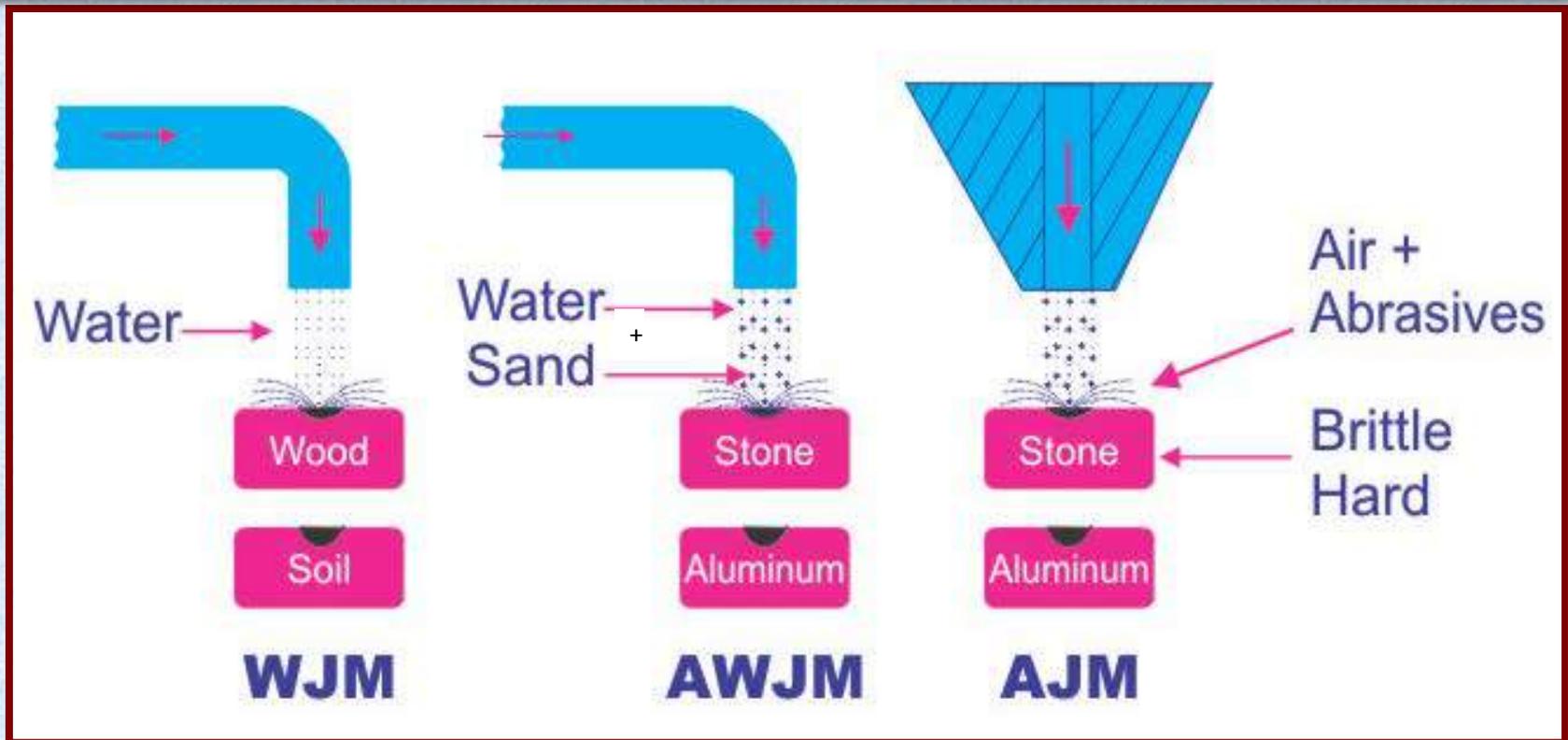
- PERFORMANCE IS INDEPENDENT OF STRENGTH BARRIER.
- PERFORMANCE DEPENDS ON THERMAL, ELECTRICAL, MAGNETIC OR / AND CHEMICAL PROPERTIES OF WORKPIECE MATERIALS.
- USE DIFFERENT KINDS OF ENERGY IN DIRECT FORM.
- IN GENERAL, LOW MRR BUT BETTER QUALITY PRODUCTS.
- COMPARATIVELY HIGH INITIAL INVESTEMENT COST OF MACHINE TOOLS AND HIGH - OPERATING COST .

# ADVANCED MACHINING PROCESSES

**CAN WATER CUT THE METALS ?**

**YES. BUT HOW?**

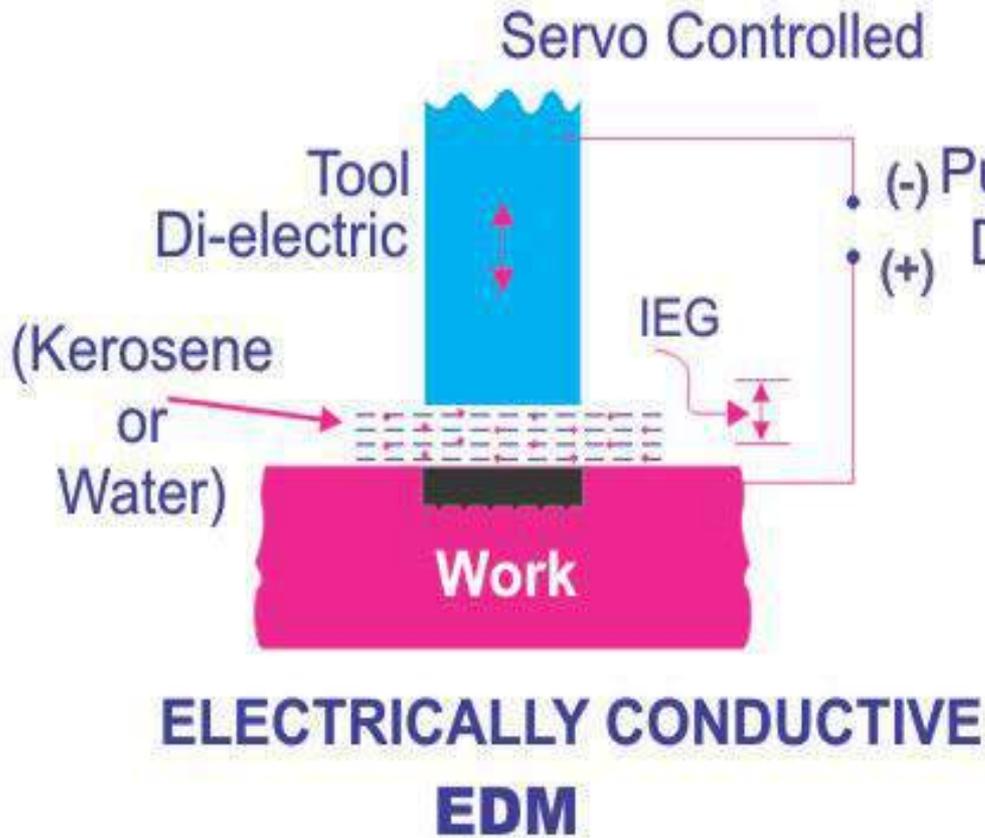
# WATER JET MACHINING (WJM), ABRASIVE WATER JET MACHINING (AWJM) , ABRASIVE JET MACHINING (AJM)



**HOW DOES IT WORK? K.E. of WATER AND / OR ABRASIVE PARTICLES MAKES IT TO HAPPEN.**

VELOCITY OF THE ABRASIVE WATER JET → AS HIGH AS 900 m/s.

# ELECTRIC DISCHARGE MACHINING



Sparking In a Switch  
↓  
Metal Removal From Both Points  
↓  
Evolution of EDM  
By USSR scientists  
**LAZERANKO Brothers**

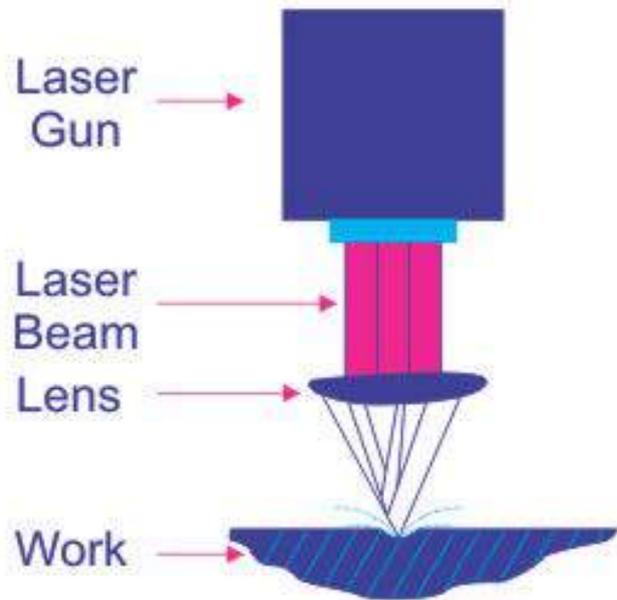


**WORN OUT MARKS**

# LASER BEAM MACHINING (LBM)



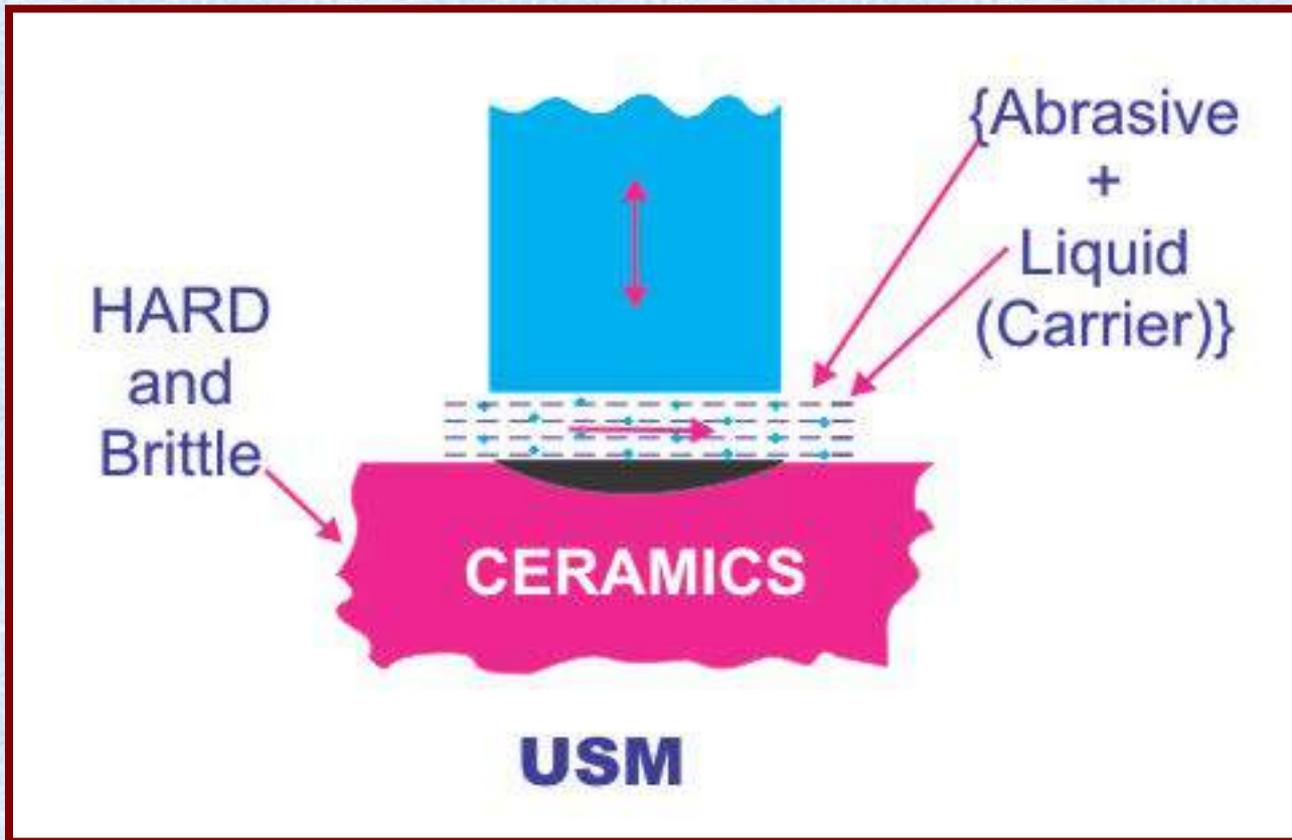
# LASER BEAM MACHINING (LBM)



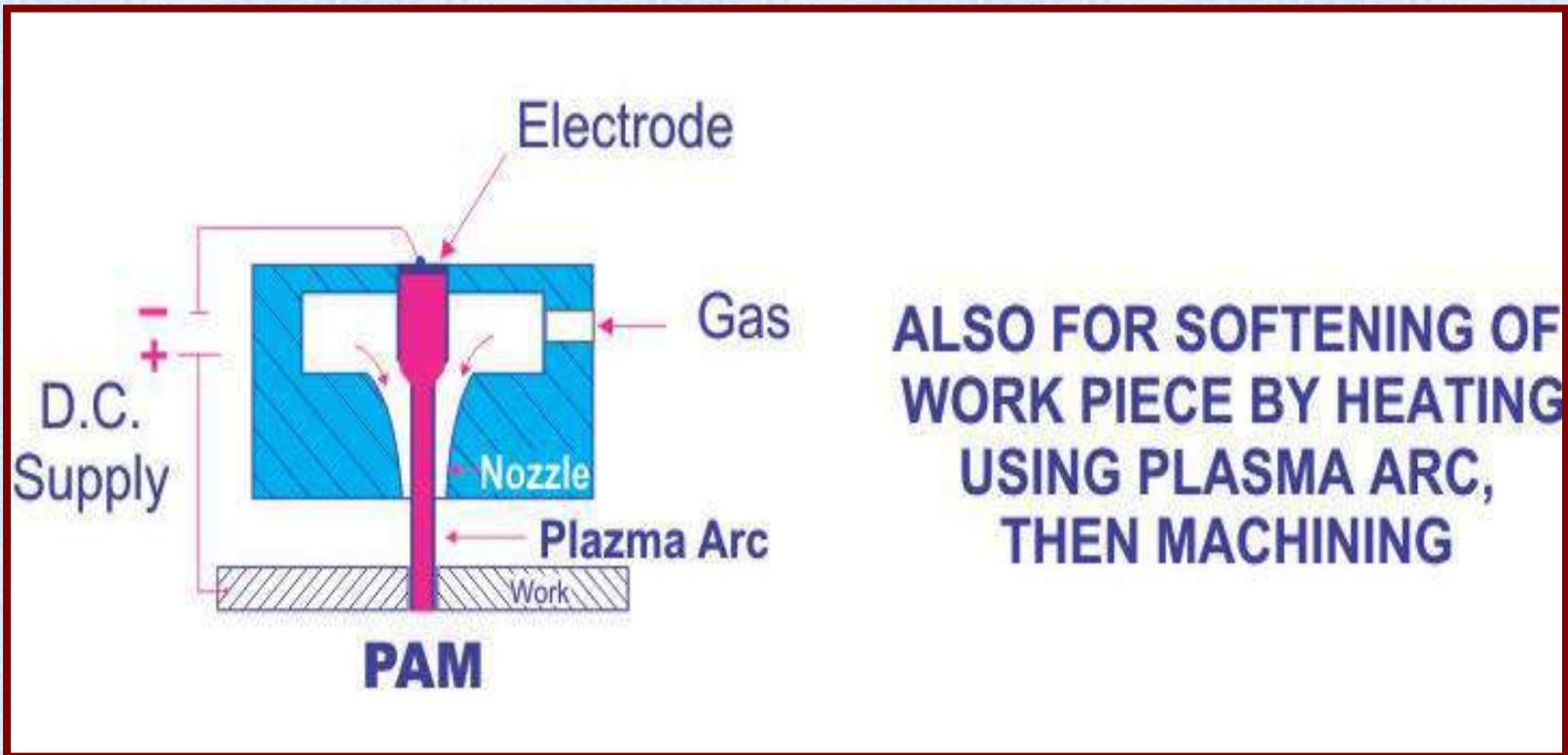
**LBM**

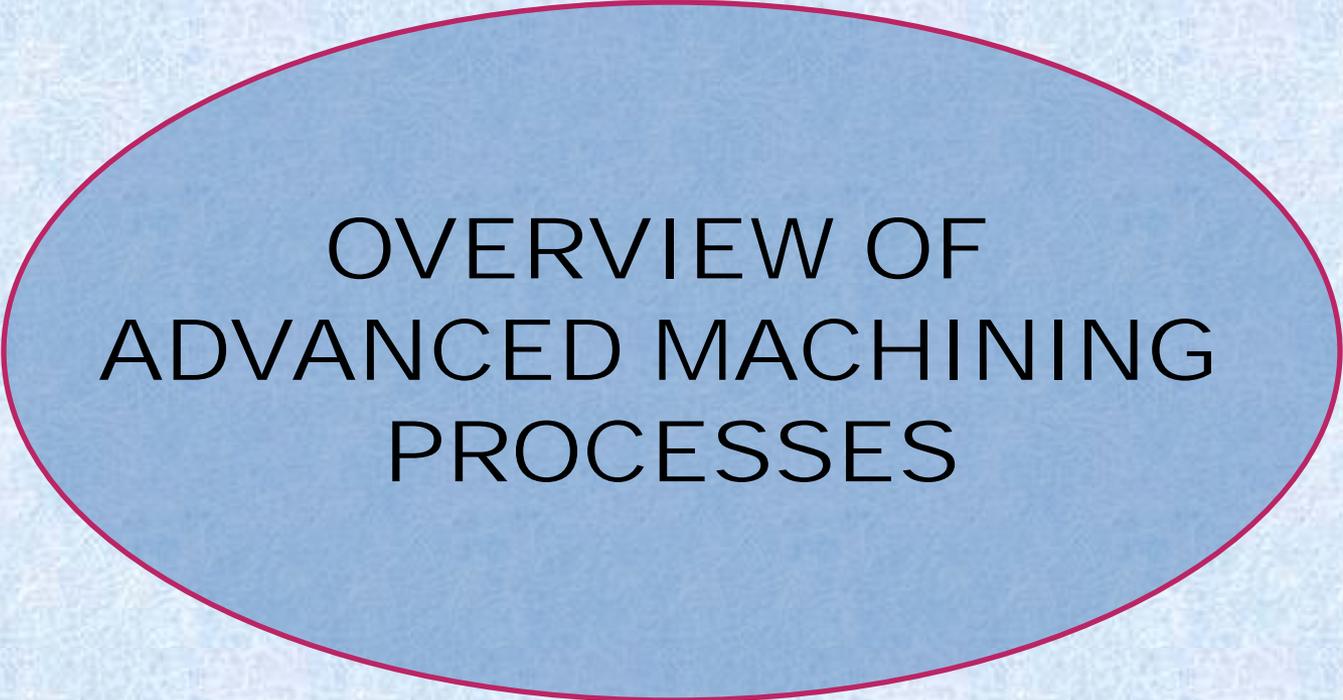
- Mechanism of material removal.  
↓  
Melting & vaporization
- For Difficult to machine materials  
High thermal conductivity.  
↓  
High Reflectivity  
↓  
Al, Cu
- Very low machining efficiency  $1 \leq \%$

# ULTRASONIC MACHINING



# PLASMA ARC MACHINING (PAM)

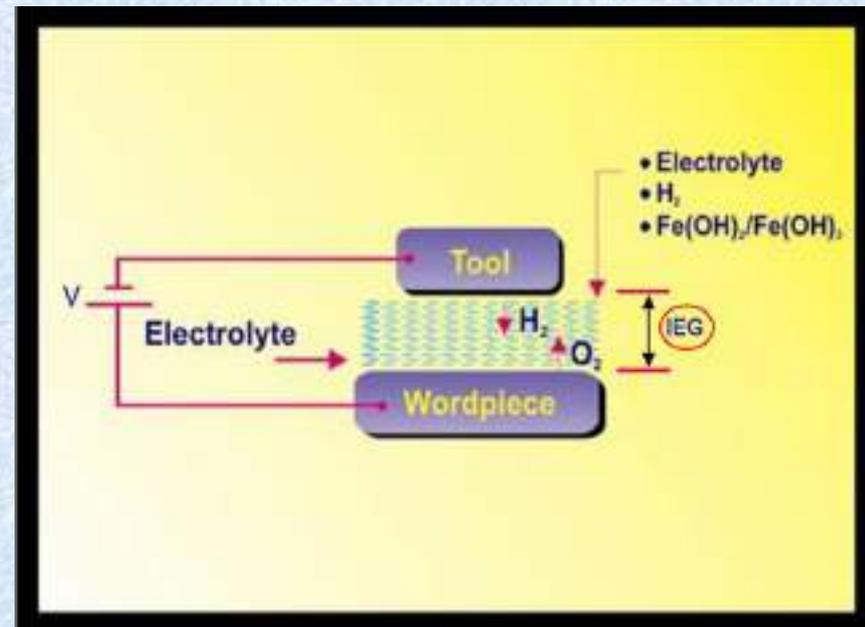
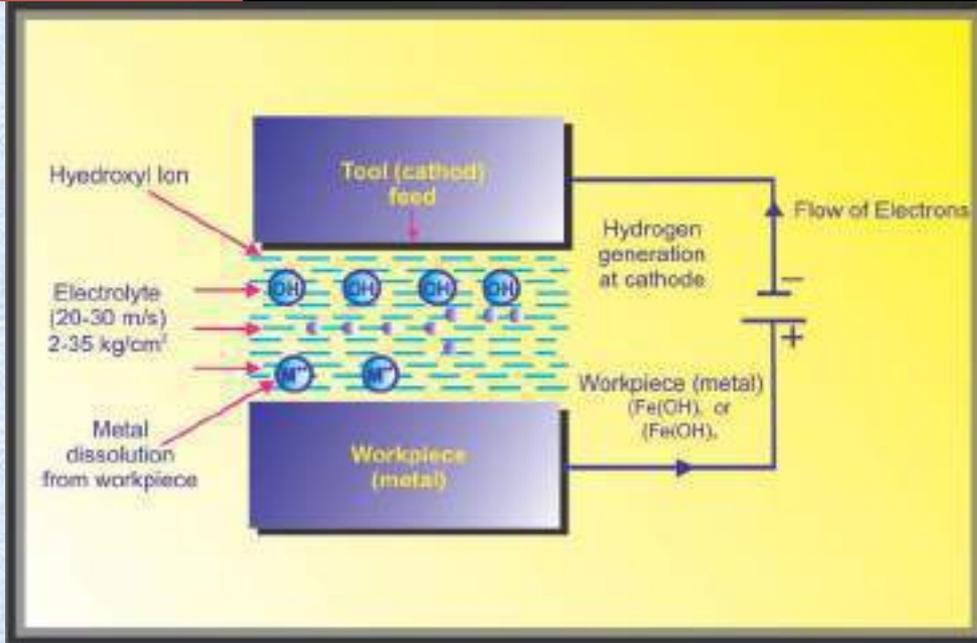




# OVERVIEW OF ADVANCED MACHINING PROCESSES

# ELECTROCHEMICAL MACHINING (ECM)

# ELECTRICHEMICAL MACHINING (ECM)



**ECM PROCESS IS ALSO KNOWN AS A CONTACTLESS ELECTROCHEMICAL FORMING PROCESS**  
**ELECTROCHEMICAL ENERGY DETACHES METAL FROM ANODE ATOM BY ATOM**

# ELECTROCHEMICAL REACTIONS

## TYPES OF ELECTROLYTES USED IN ECM



**$\text{Fe}(\text{OH})_2$  ,  $\text{Fe}(\text{OH})_3 \rightarrow$  INSOLUBLE IN WATER**

**POSITIVE IONS CONVERT AS HYDROXIDES (FERROUS OR FERRIC HYDROXIDE IN CASE OF IRON AS ANODE/ WORK MATERIAL)**

**IEG < 1 mm, VOLTAGE  $\rightarrow$  8-20**

**NO ELECTROLYTE IS BEING CONSUMED IN THE PROCESS**

# WORKING PRINCIPLE OF ECM

## FARADAY'S LAWS OF ELECTROLYSIS



$$m \propto itE$$

MASS OF DISSOLVED METAL

GRAM CHEMICAL EQUIVALENT =  $A / Z$

CURRENT

TIME

$A \rightarrow$  ATOMIC MASS OF ANODE,  $Z \rightarrow$  VALENCY OF DISSOLUTION OF ANODE

# MATERIAL REMOVAL IN ECM

MATERIAL REMOVAL (m) IN ECM FOLLOWS FARADAY'S LAWS  
OF ELECTROLYSIS:

$$m = \frac{ItE}{F} \quad \text{.....(1)}$$

MATERIAL REMOVAL RATE (MRR) CAN BE OBTAINED AS

$$\frac{m}{t} = \dot{m} = \frac{IE}{F} \quad \text{.....(1a)}$$

Where, 'm' is amount of material removed in grams, 'I' is current flowing through the IEG in Amperes, 't' is time of current flow (or ECM), 'E' is gram chemical equivalent of anode material, 'F' is Faraday's constant (Coulombs or A.s) or constant of proportionality. and  $\dot{m}$  is material removal rate in g/s.

# MATERIAL REMOVAL IN ECM

MRR CAN BE OBTAINED AS

$$\frac{\rho_a V_a}{t} = \frac{\rho_a A_a (y_a)}{(t)} = \frac{IE}{F}$$

WHERE,  $\rho_a$  = DENSITY OF ANODE,  $V_a$  = VOLUME OF MATERIAL REMOVED FROM THE ANODE IN TIME 't',  $A_a$  = X-SECTIONAL AREA ON THE ANODE FROM WHICH MATERIAL IS BEING REMOVED IN TIME 't',  $y_a$  IS THE THICKNESS OF MATERIAL REMOVED IN TIME 't'.  $\Delta V$  IS OVER POTENTIAL,  $k$  = ELECTROLYTE'S ELECTRICAL CONDUCTIVITY

# MATERIAL REMOVAL IN ECM

FROM ABOVE EQUATION, WE CAN WRITE

$$\therefore MRR_l = \frac{(y_a)}{(t)} = \frac{IE}{F \rho_a A_a}$$

$$MRR_l = \frac{JE}{F \rho_a} \quad \text{.....(2)}$$

(J = CURRENT DENSITY = I/A<sub>a</sub>)

ABOVE EQUATION CAN BE WRITTEN AS

$$MRR_l = \left( \frac{V - \Delta V}{A_a} \right) \left\{ \frac{kA_a}{y} \right\} \frac{E}{F \rho_a}$$

$$J = I/A_a = V/R = V/(\rho l/A)$$

$$\rho = (1/k)$$

$$J = ((V - \Delta V)/A) (kA/y)$$

$\rho$  = Resistance

Anode density

# THERMAL MICROMACHINING PROCESSES

## ELECTRIC DISCHARGE MICROMACHINING

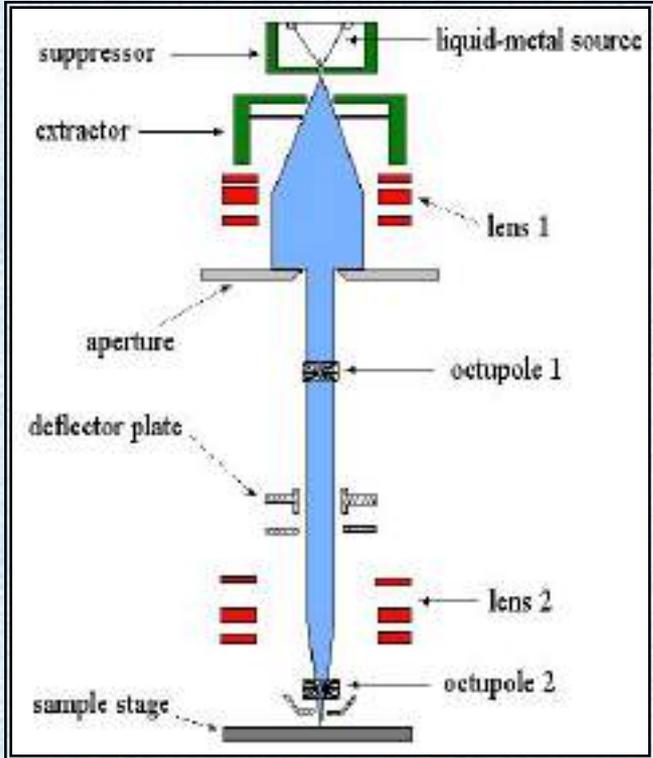
### BEAM MICROMACHINING



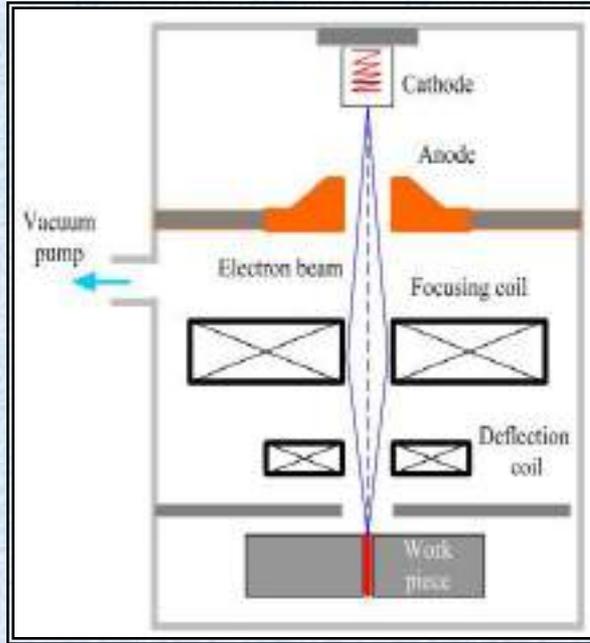
1. LASER BEAM MICROMACHINING
2. ELECTRON BEAM MICROMACHINING
3. ION BEAM MICROMACHINING  
(NOT A THERMAL PROCESS)

# BEAM TECHNOLOGY

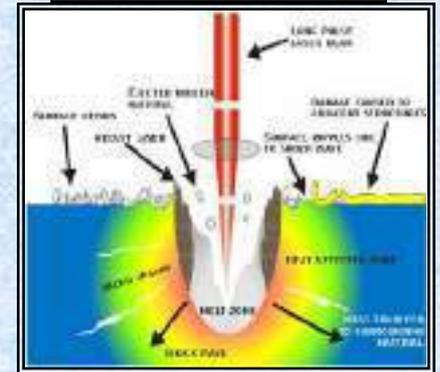
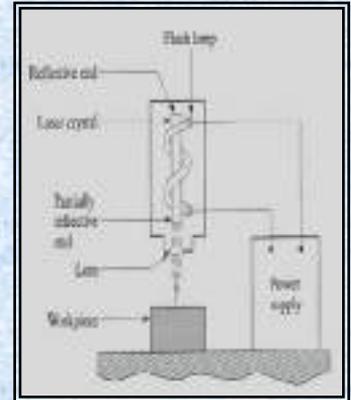
## IBM



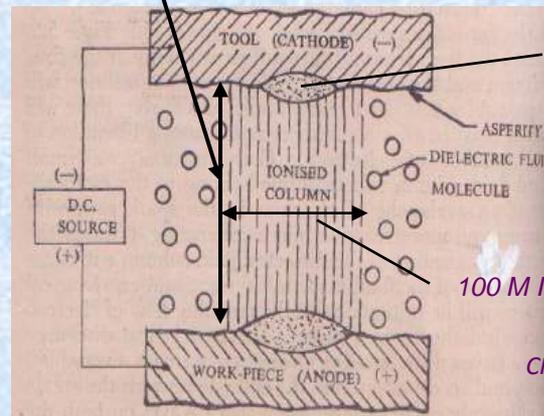
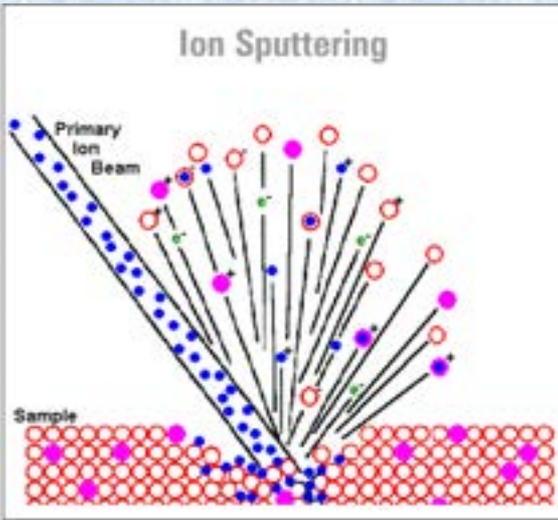
## EBM



## LBM



IEG = A FEW HUNDRED  $\mu\text{m}$

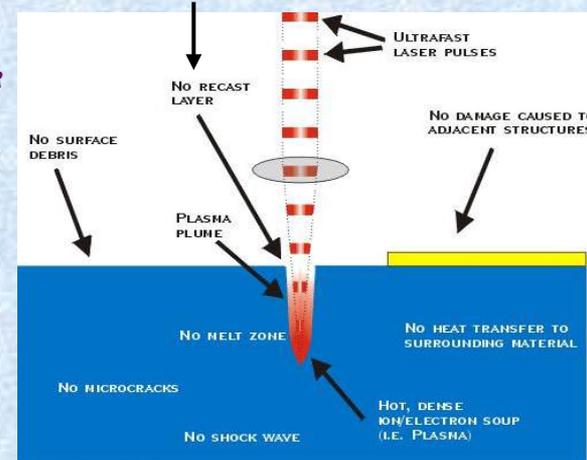


CRATER

100 MICRONS

CRATER

Dr. V.K. Jain, IIT Kanpur, vkjain@iitk.ac.in



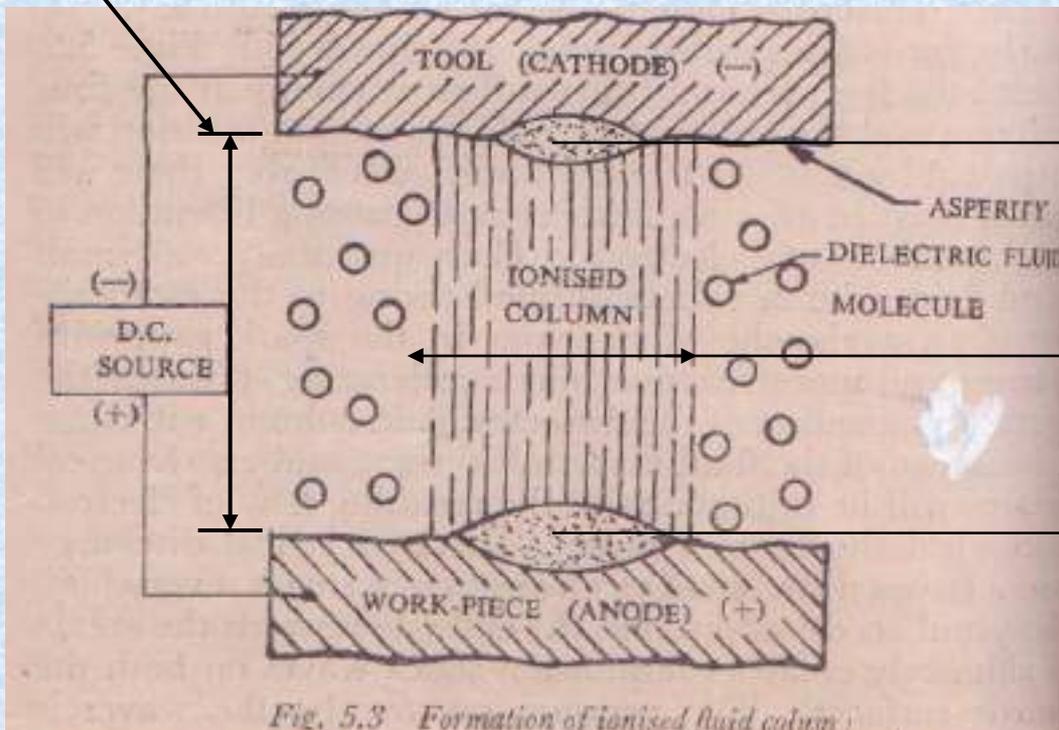
SHORT PULSE LASER MACHINING

# ELECTRIC DISCHARGE MACHINING (EDM)

# ELECTRIC DISCHARGE MACHINING (EDM)

- SPARKS CREATED DELIBERATELY
- HEAT IN A LOCALIZED AREA

IEG = A FEW HUNDRED  $\mu\text{m}$



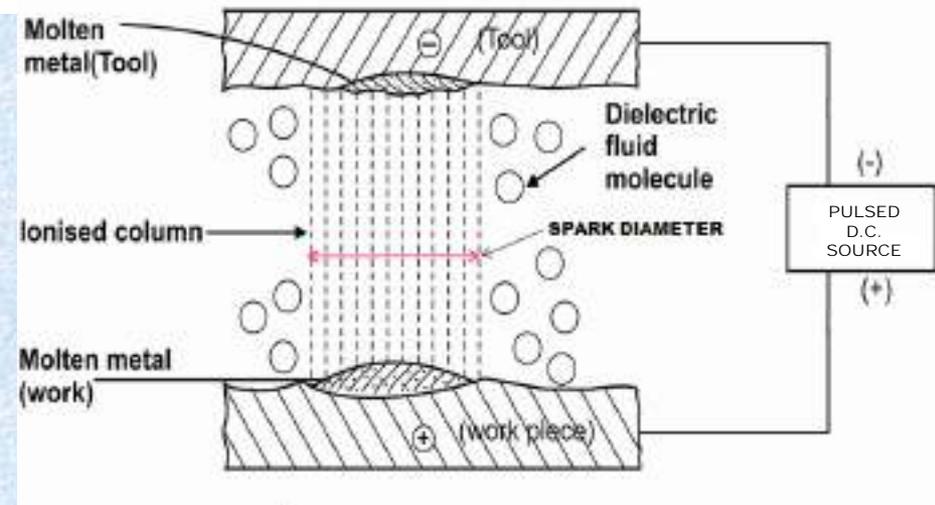
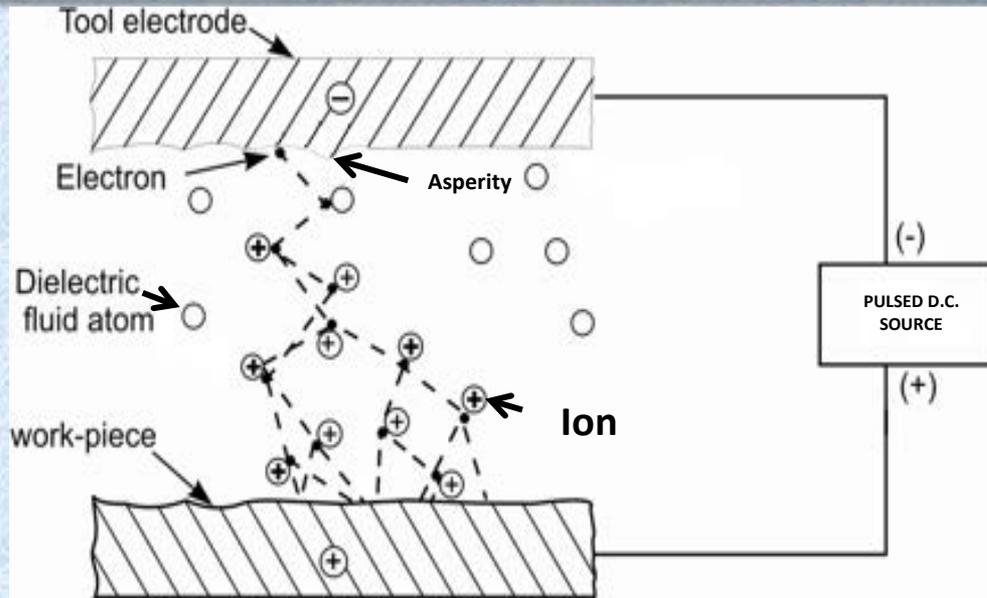
CRATER  
MELTING AND /  
OR VAPORIZATION

100 MICRONS

CRATER

Fig. 5.3 Formation of ionised fluid column

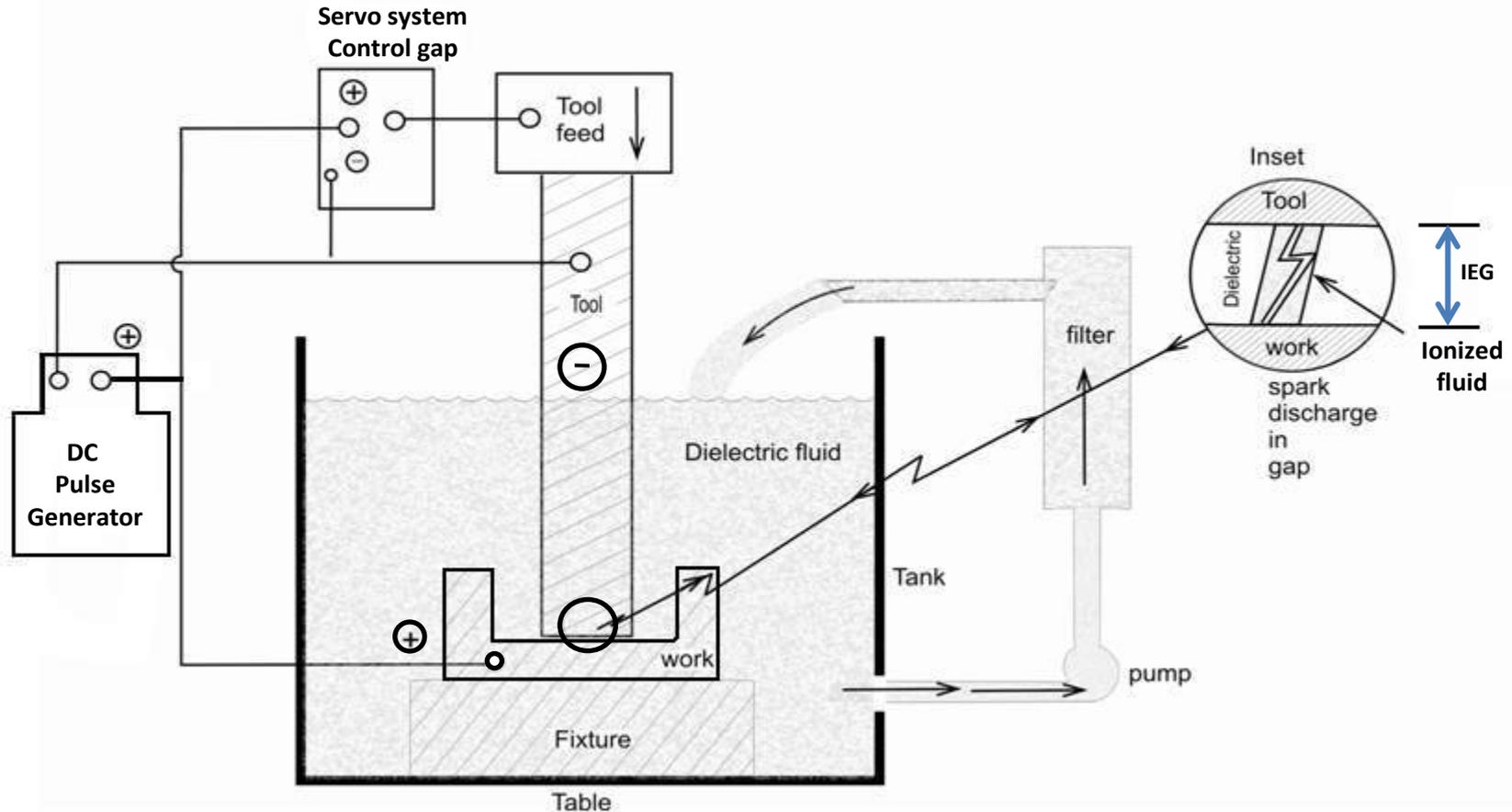
# ELECTRIC DISCHARGE MACHINING : HOW SPARKING TAKES PLACE?



# EDM: WORKING PRINCIPLE

- ❖ BREAK DOWN OF DIELECTRIC (AT PRE DETERMINED ELECTRIC FIELD) OF DIELECTRIC (USUALLY KEROSENE OR WATER) TAKES PLACE BETWEEN TWO ELECTRODES (TOOL & WORKPIECE).
- ❖ DIELECTRIC IONIZATION → MOLECULES (ELECTRONS FROM CATHODE COLLIDE THE MOLECULES ) SPLIT INTO IONS, AND ELECTRONS.
- ❖ IONS → MOVE TOWARDS CATHODE AND ELECTRONS MOVE TOWARDS → ANODE
- ELECTRONS HIT THE CATHODE AND IONS HIT ANODE
- DUE TO THEIR K.E., THEY PRODUCE HEAT ON CATHODE (LESS) AND ANODE (MORE)
- THIS HEAT MELTS AND EVEN VAPORIZES A SMALL PART OF CATHODE AND ANODE.

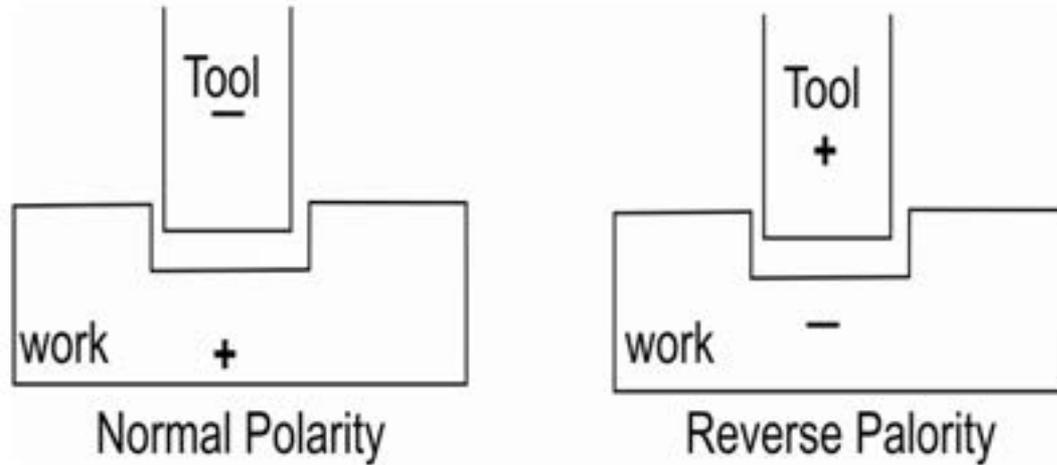
# ELECTRIC DISCHARGE MACHINING (EDM) : MACHINE ELEMENTS



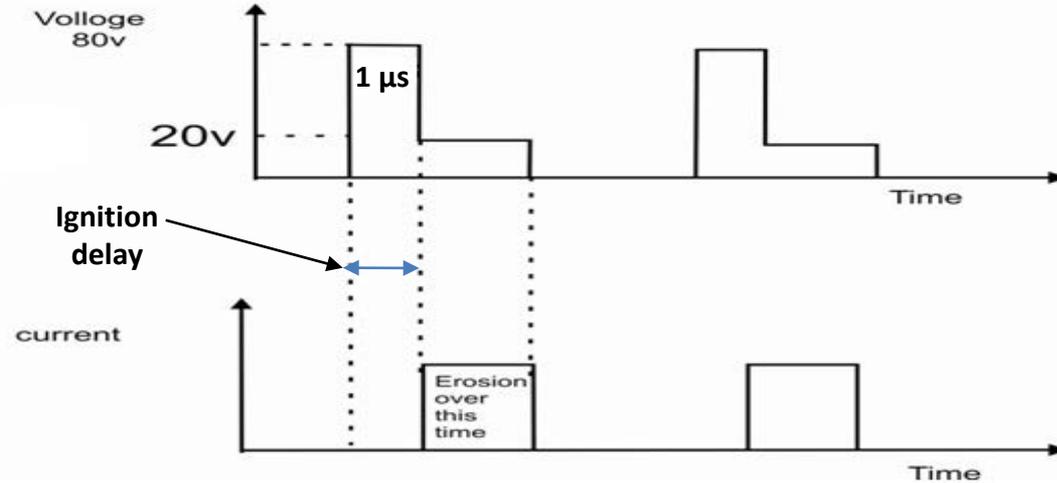
**REPLICA OF THE TOOL → WORKPIECE**

# ELECTRIC DISCHARGE MACHINING (EDM)

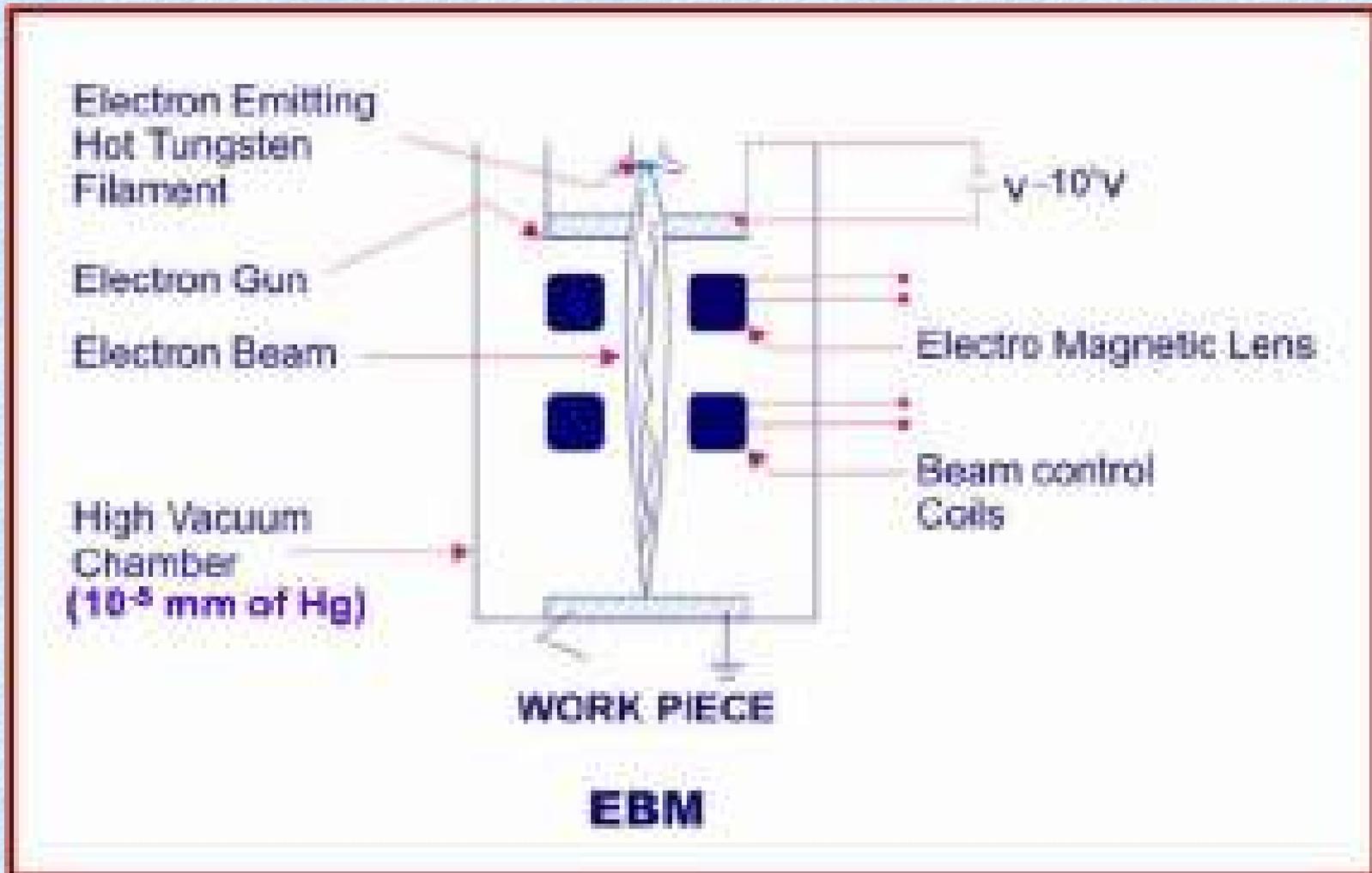
## POLARITY IN EDM



## VOLTAGE / CURRENT PULSES IN EDM



# ELECTRON BEAM MACHINING (EBM)



# FOCUSSED ION BEAM MACHNING (IBM)

- ◆ SPUTTERING OFF: KNOCKING OUT ATOMS FROM THE WORK-PIECE SURFACE BY THE KINETIC MOMENTUM TRANSFER FROM INCIDENT ION TO THE TARGET ATOMS
- ◆ REMOVAL OF ATOMS WILL OCCUR WHEN THE ACTUAL ENERGY TRANSFERRED EXCEEDS THE USUAL BINDING ENERGY.

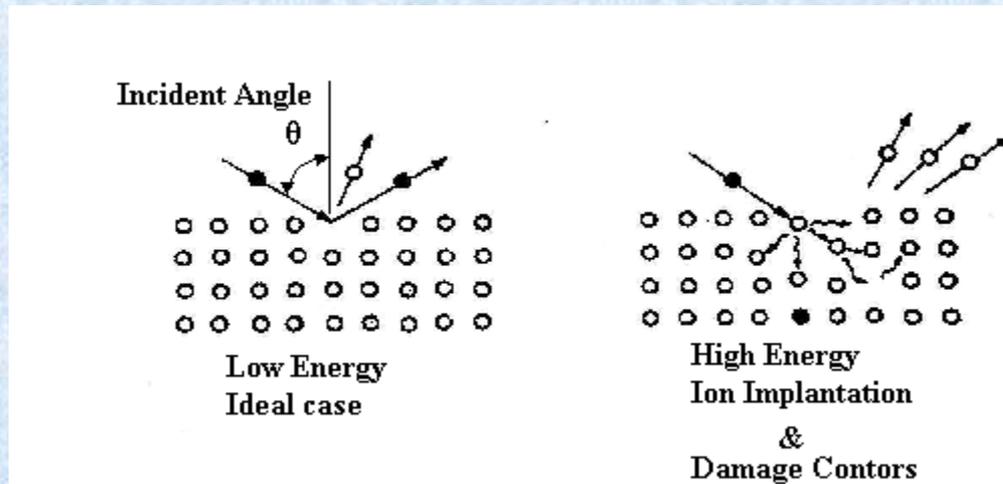


FIG. SCHEMATIC ILLUSTRATION

- ◆ AT SUFFICIENTLY HIGH ENERGY, THE CASCADING EVENTS WILL PENETRATE MORE DEEPLY INTO THE SOLID, SEVERAL ATOMS OR MOLECULES WILL BE EJECTED OUT AND THE BOMBARDING ION WILL BECOME IMPLANTED DEEP WITHIN THE MATERIAL.

# MECHANICAL MICROMACHINING PROCESSES

**ULTRASONIC MICROMACHINING**

**ABRASIVE JET MICROMACHINING**

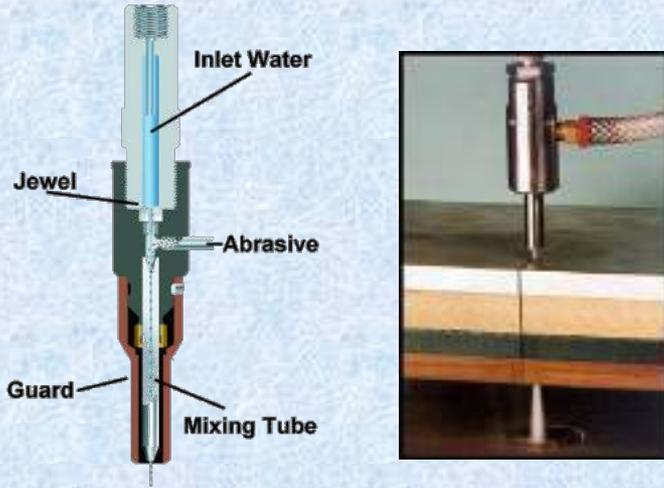


**1. WATERJET MICROMACHINING**

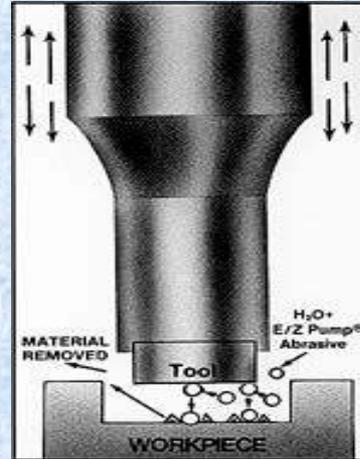
**2. ABRASIVE WATER JET MICROMACHINING**

# PRINCIPLE OF MECHANICAL MICROMACHINING MECHANISM

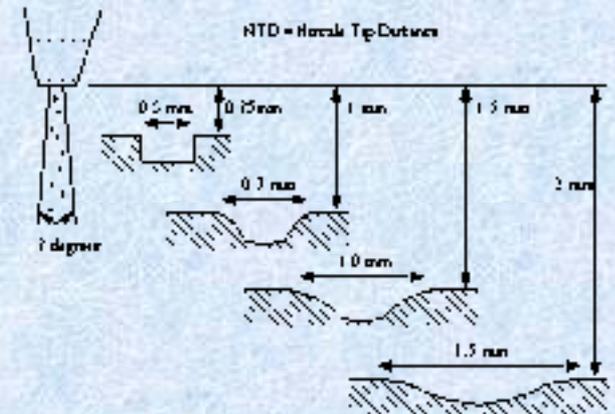
## ABRASIVE WATER JET MACHINING



## ULTRASONIC MACHINING

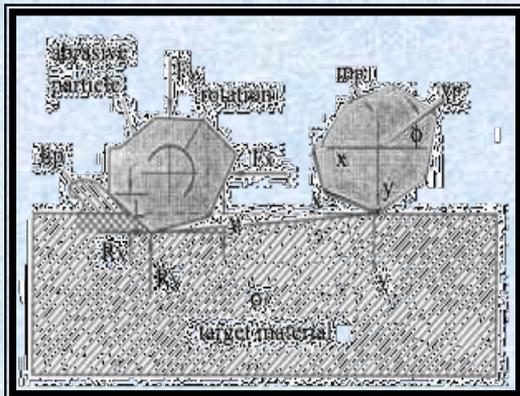


## ABRASIVE JET MACHINING

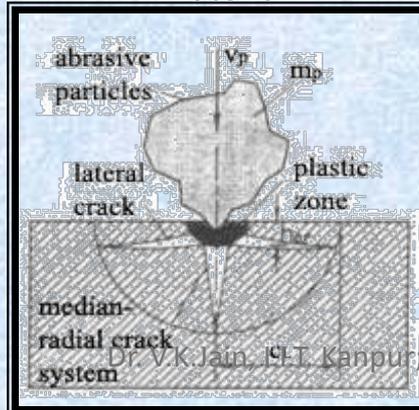


## AWJM, AJM, USM

### Mechanism of material removal in ductile material

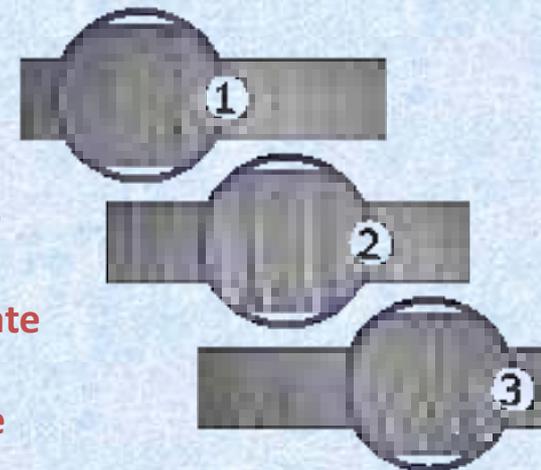
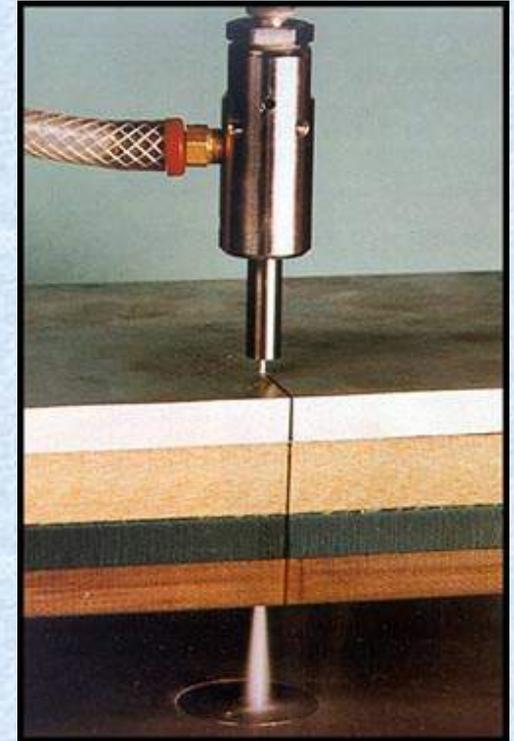
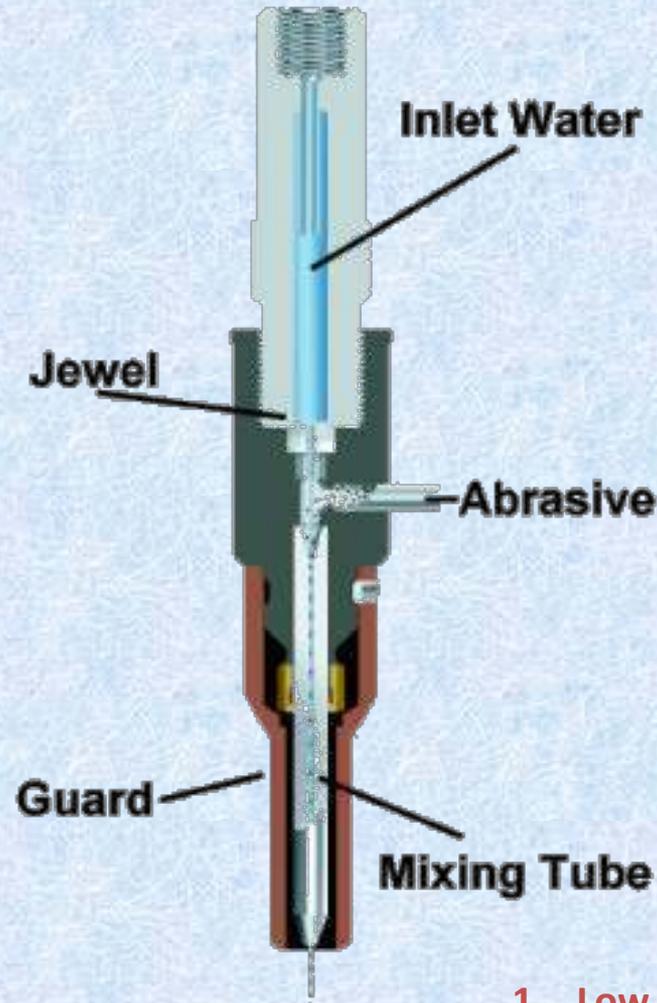
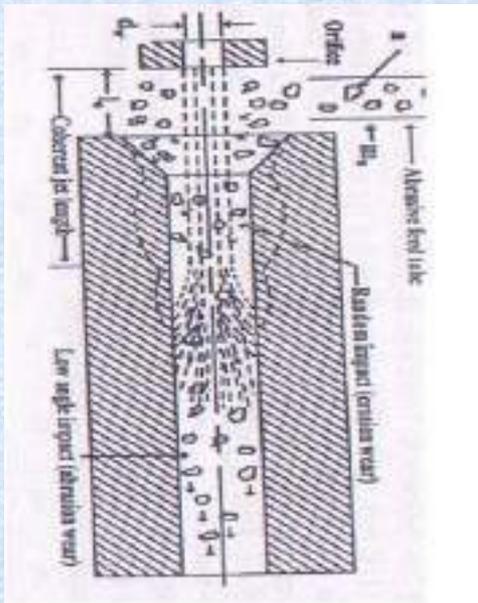


### Mechanism of material removal in brittle material



FORCES ACTING ON EACH PARTICLE AND PARTICLE SIZE WILL DEC IDE THE SCALE OF MATERIAL REMOVED : MACRO, MICRO, NANO

# ABRASIVE WATER JET MICRO-MACHINING (AWJM)



1. Low feed rate

2. Medium feed rate

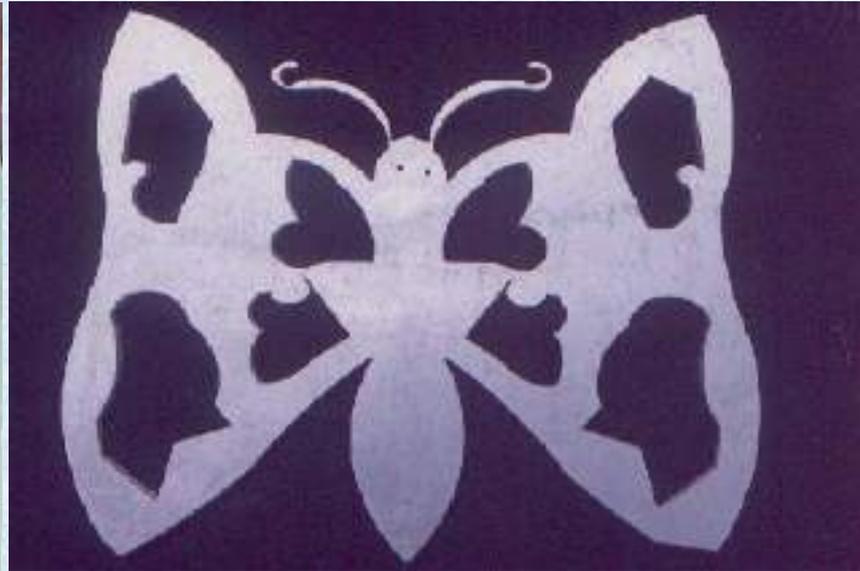
3. High feed rate

# APPLICATIONS OF ABRASIVE WATER JET CUTTING (AWJC)



Granite cutting

(COURTESY : IITM CHENNAI)



# Material Removal Processes

```
graph TD; A[Material Removal Processes] --> B[Micro/nano machining]; A --> C[Micro/nano finishing]; B --> D[Traditional machining processes]; B --> E[Advanced machining processes]; C --> F[Traditional finishing processes]; C --> G[Advanced finishing processes];
```

## Micro/nano machining

Traditional machining processes

Advanced machining processes

## Micro/nano finishing

Traditional finishing processes

Advanced finishing processes

## Micro-manufacturing

A set of processes used to fabricate features, components, or systems with dimensions most conveniently described in micrometers

# MICROMACHINING : AN OVERVIEW

## Why miniaturization?

Minimizing energy and materials use in manufacturing

Reduction of power budget

Faster devices

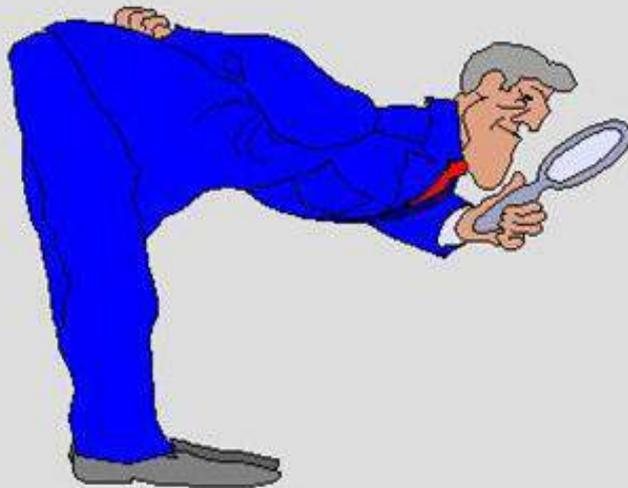
Increased selectivity and sensitivity

Improved accuracy and reliability

Cost / performance advantages

Integration with electronics, simplifying systems

# Size Comparisons in Micromanufacturing



- 100 micrometers ~ paper thickness, human hair
- 8 micrometers ~ red blood cell, capillaries
- 0.5 micrometers ~ visible light, machining tolerance
- 0.07 micrometers ~ year 2010 IC production design rules
- 0.0003 micrometers ~ atomic spacing in solids



# Methods of Micro-manufacturing

**Material deposition**

Electro chemical spark deposition

Electro discharge deposition

Chemical vapor deposition

Physical vapor deposition

Rapid prototype / rapid tooling

LIGA

**Material Removal**

Traditional material removal processes

Advanced material removal processes

**Forming / shaping**

Rolling

Forging

Extrusion & drawing

Sheet metal

**Joining**

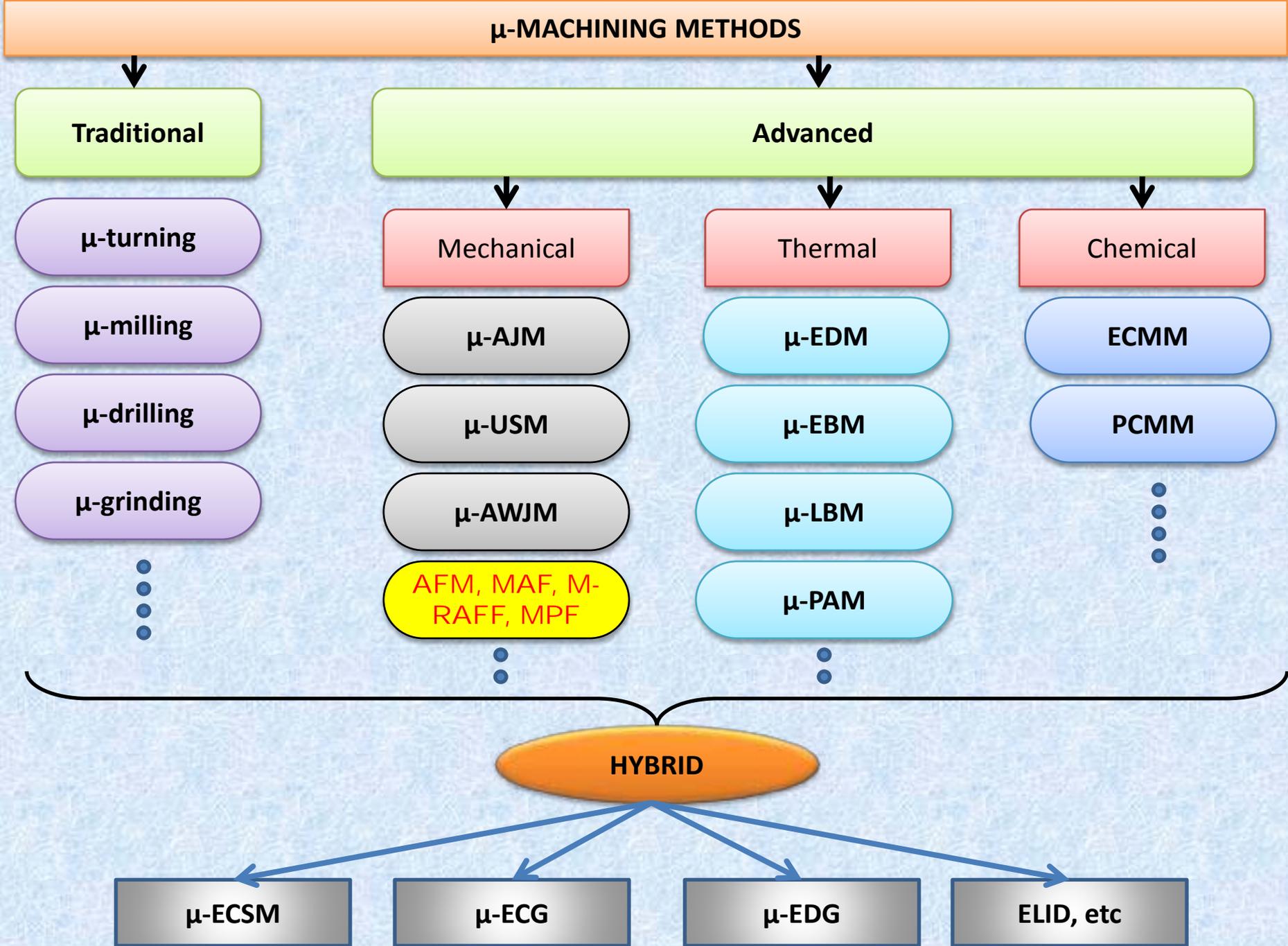
Welding

Brazing

Soldering

**Casting**

**MICROFABRICATION IS GOING TO WITNESS AN EXCELLENCE IN R & D AT A REMARKABLE RATE**



# MICRO MACHINING

Micro



Machining

Removal of material at micro level

1. Macro components but material removal is at micro/nano level
2. Micro/nano components and material removal is at micro/nano level (Ex. MEMS, NEMS)



LEG OF A HOUSE FLY

SIZE : 2mm x 2mm

Unfortunately , the present day notion is



Machining of highly miniature components with miniature features.

**Literally it should NOT be so**

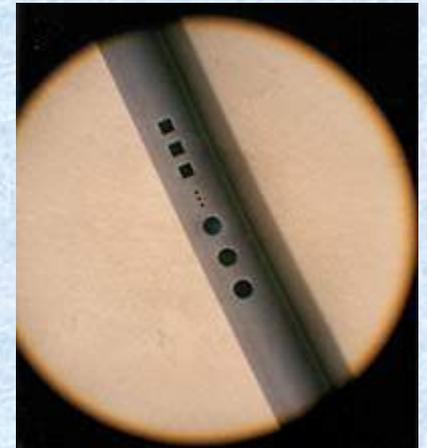
MORE CORRECT DEFINITION IS material removal is at micro/nano level  
WITH NO CONSTRAINT ON THE SIZE OF THE COMPONENT

# SOME MICROMACHINED PARTS



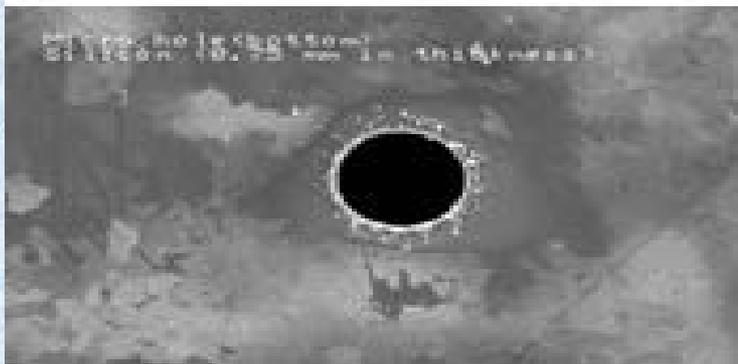
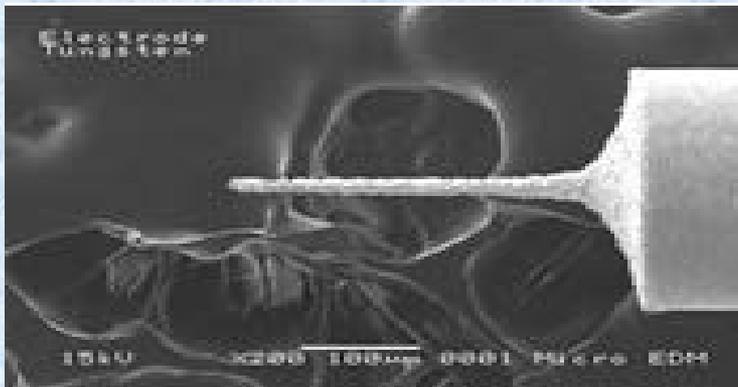
**LASER-CUT STENTLIKE PATTERN IN MINIATURE STAINLESS- STEEL TUBE WITH 1.25-mm OD.**

**LASER-DRILLED HOLE (DIA. 15  $\mu\text{m}$ ) PATTERN IN POLYURETHANE TUBE**

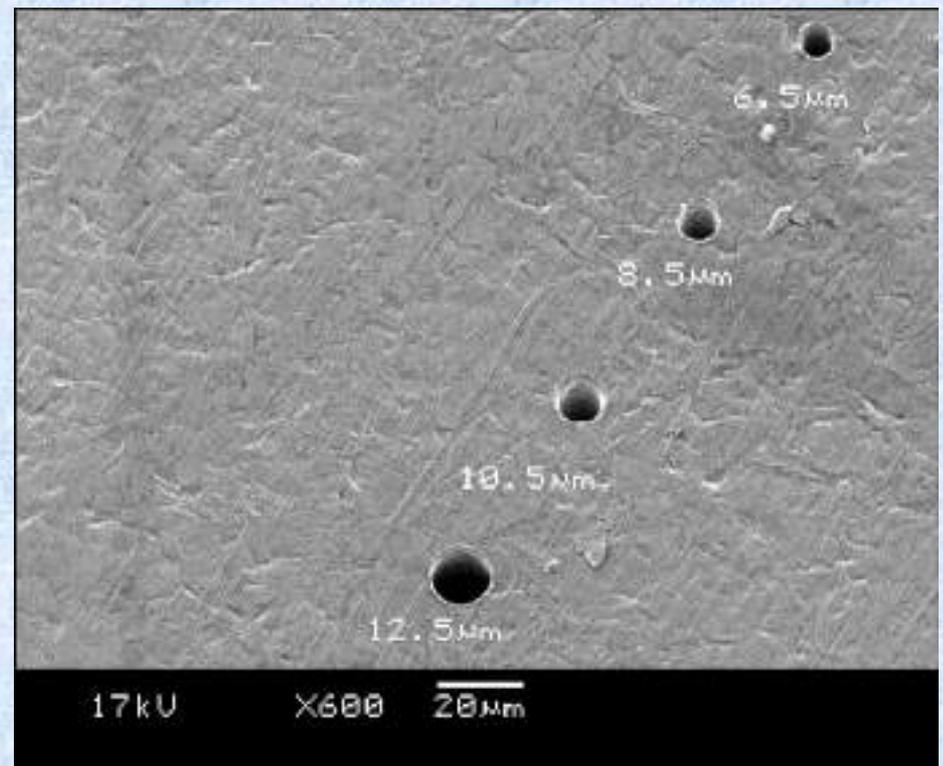


**ELECTRO DISCHARGE  
MICROMACHINING  
(EDMM)**

# EXAMPLES OF EDM



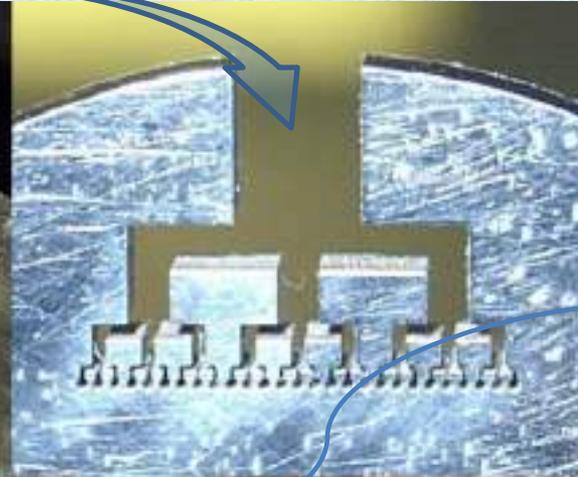
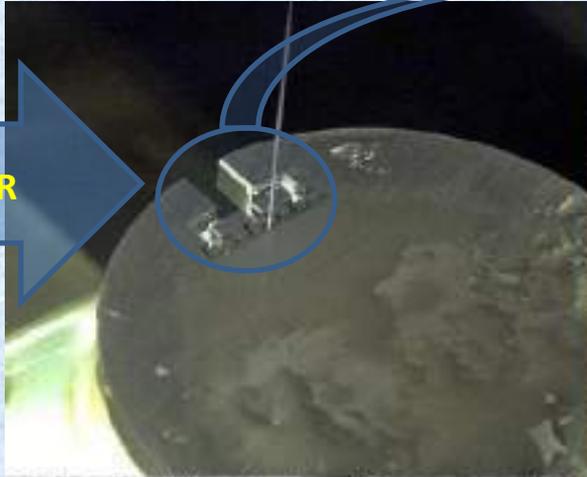
**30-micron shafts and 50-micron holes produced by micro-EDM.**



**Holes as small as 6.5 microns in diameter and an aspect ratio of 7.5**

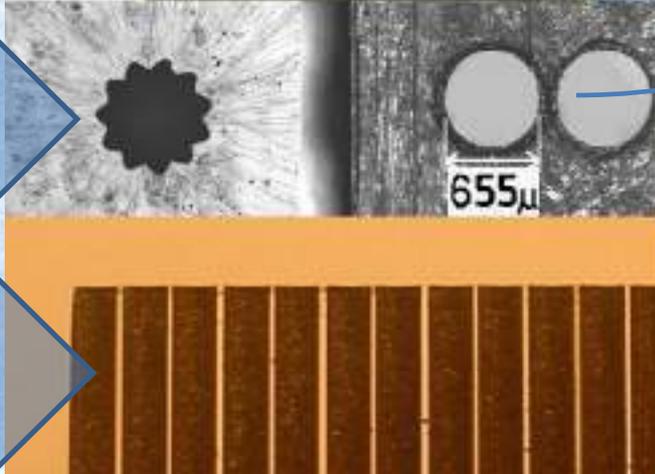
# EXAMPLES OF EDMM

MICROFLUIDICS MIXER

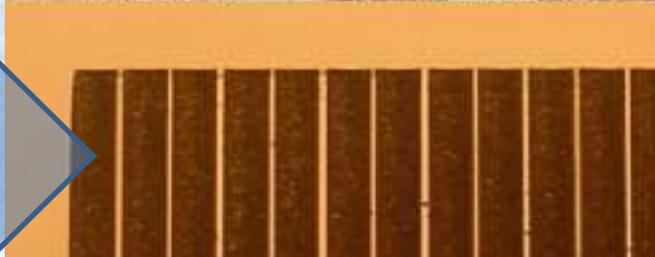


PIN OVER  
MOULDING  
JIG (655  $\mu$   
HOLES)

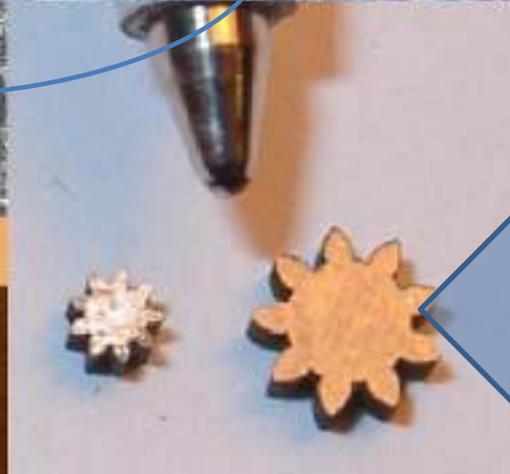
0.52 mm DIA  
EXTRUSION DIE



LADDER WITH 100  $\mu$ m  
GAP BETWEEN TEETH



MICRO  
GEARS(DIA 0.52  
mm)



# **LASER BEAM MICROMACHINING (LBMM)**

# BASIC PRINCIPLES OF LASER

- **LIGHT AMPLIFICATION BY STIMULATED EMISSION OF RADIATION.**
- **LIGHT ENERGY OF A PARTICULAR FREQUENCY CAN BE USED TO STIMULATE THE ELECTRONS IN AN ATOM TO EMIT ADDITIONAL LIGHT WITH EXACTLY THE SAME CHARACTERISTICS AS THE ORIGINAL STIMULATING LIGHT SOURCE.**
- **PHOTON ENERGY IS PROPORTIONAL TO FREQUENCY BUT INVERSELY PROPORTIONAL TO WAVELENGTH.**
- **THE PHOTON STIMULATES THE ATOM, CAUSING IT TO EMIT AN ADDITIONAL PHOTON WITH IDENTICAL CHARACTERISTICS TO THE STIMULATING PHOTON.**

# PROPERTIES OF LASER BEAM

- MONOCHROMATIC – **SINGLE WAVELENGTH.**
- COHERENT – **SAME PHASE RELATIONSHIP.**
- DIRECTIONAL – **LOW DIVERGENCE, BEAM SPREADS VERY LITTLE.**
- INTENSE – **HIGH DENSITY OF USABLE PHOTONS.**

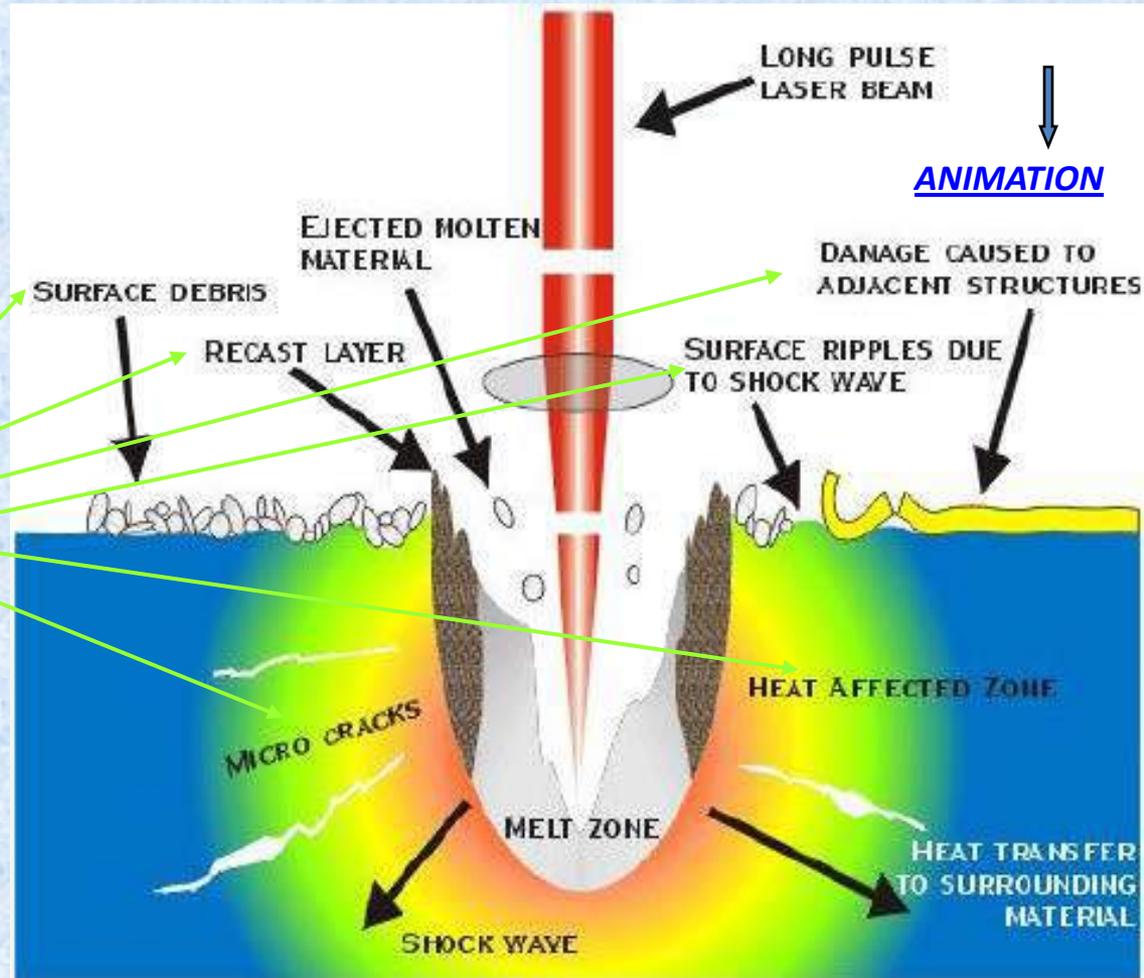
TWO TYPES OF LASERS: CONTINUOUS WAVE AND PULSED LASERS  
LONG PULSED LASERS AND SHORT PULSED LASERS

# TYPES OF LASERS

## TIME SCALES:

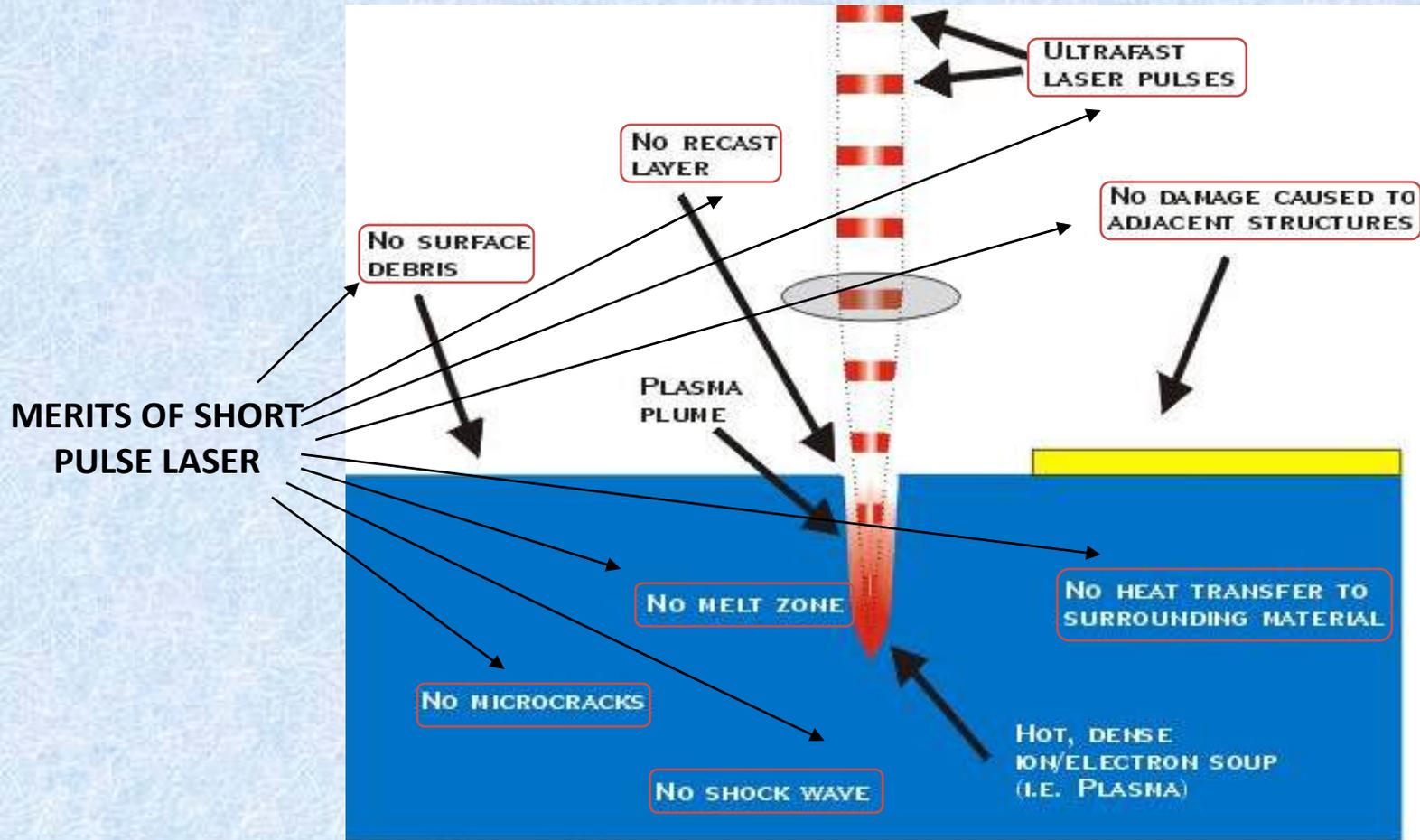
Millisecond	$1 \cdot 10^{-3}$ second
Micro second	$1 \cdot 10^{-6}$ second
Nano second	$1 \cdot 10^{-9}$ second
Pico second	$1 \cdot 10^{-12}$ second
Femto second	$1 \cdot 10^{-15}$ second

# LONG PULSE LASER MACHINING

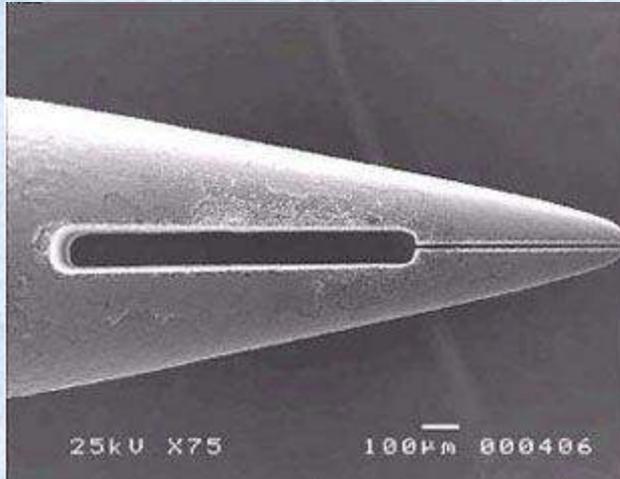


DEMERITS OF LONG PULSE LASER

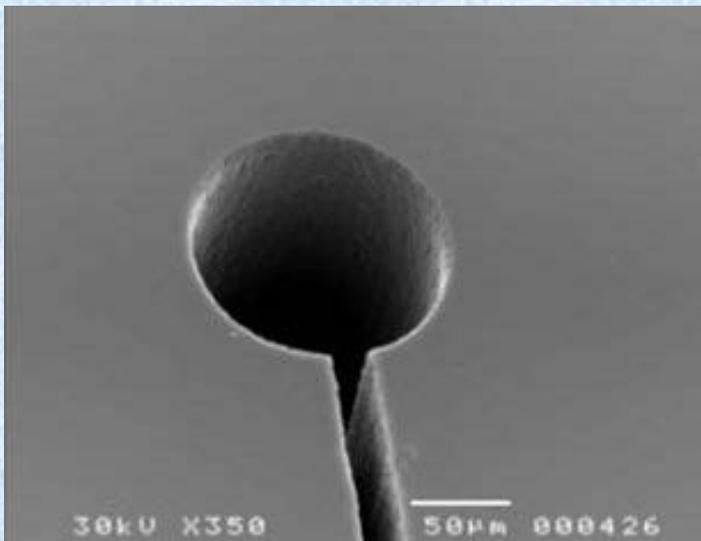
# SHORT PULSE LASER MACHINING



# APPLICATIONS OF LBM

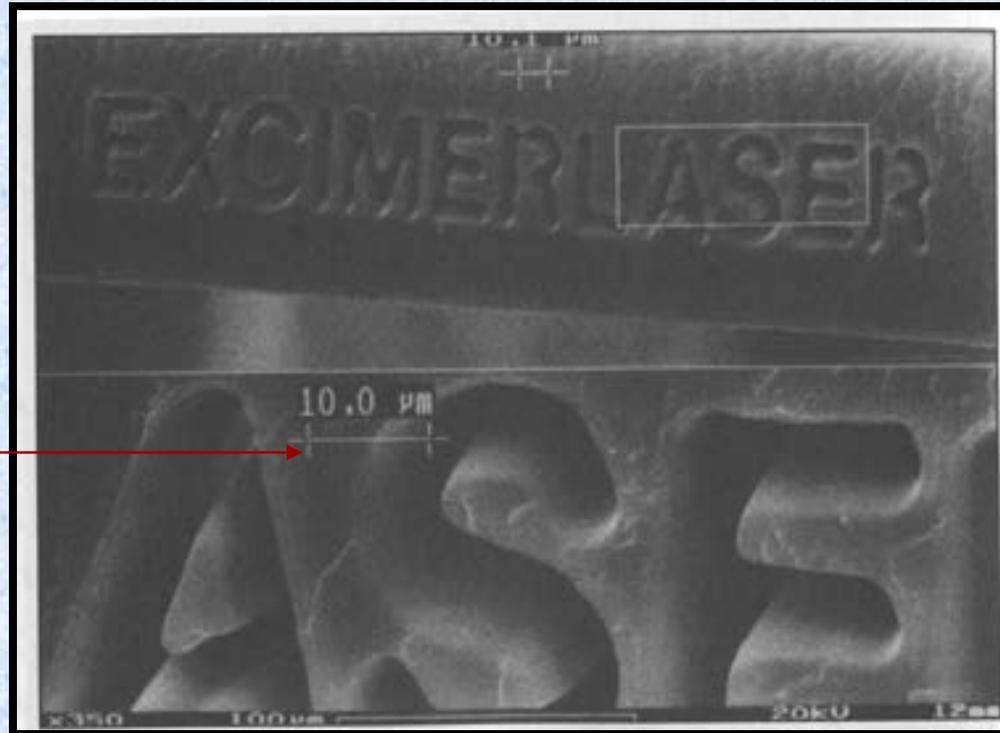


MICRO CUTTING IN A TUNGSTEN PIN USING  
511nm ND LASER



MICRO FLUIDIC DEVICE IN SILICON SHOWING  
LASER DRILLED VIA HOLE AND CONNECTING  
CHANNEL

# LASERS AND THEIR CONFIGURATION

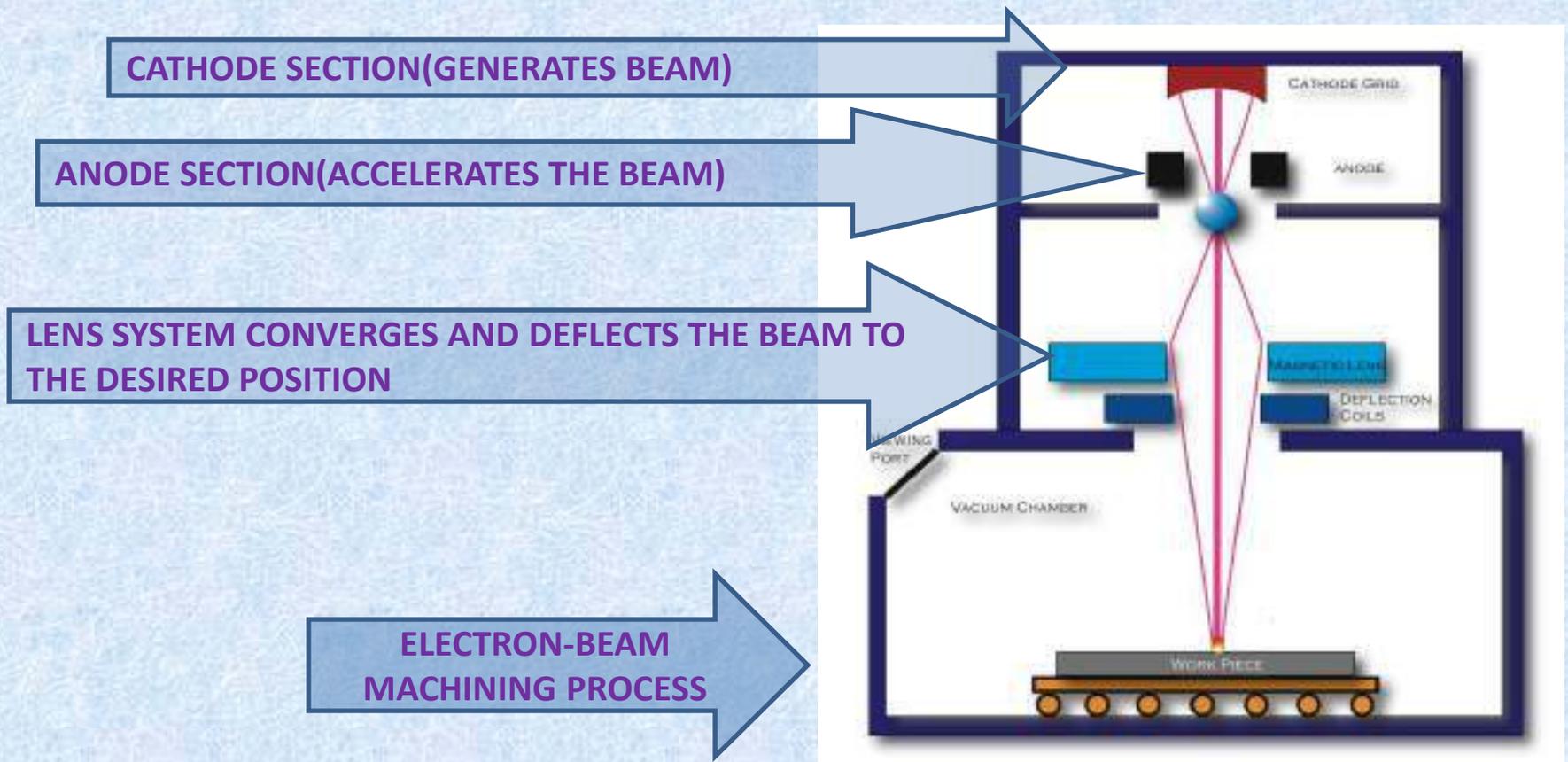


**MICRO MACHINED LETTERS ON A SINGLE HUMAN HAIR  
NOTE THE CLARITY OF THE LETTERS IN THE CLOSE-UP VIEW**

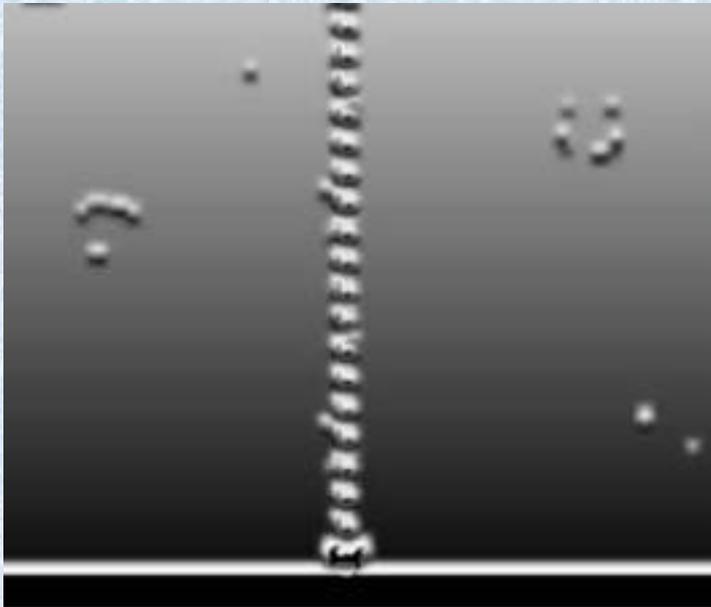
# **ELECTRON BEAM MICROMACHINING (EBMM)**

# BASICS OF EBM

- IT WORKS IN MUCH THE SAME WAY AS A CATHODE RAY TUBE IN A TELEVISION.

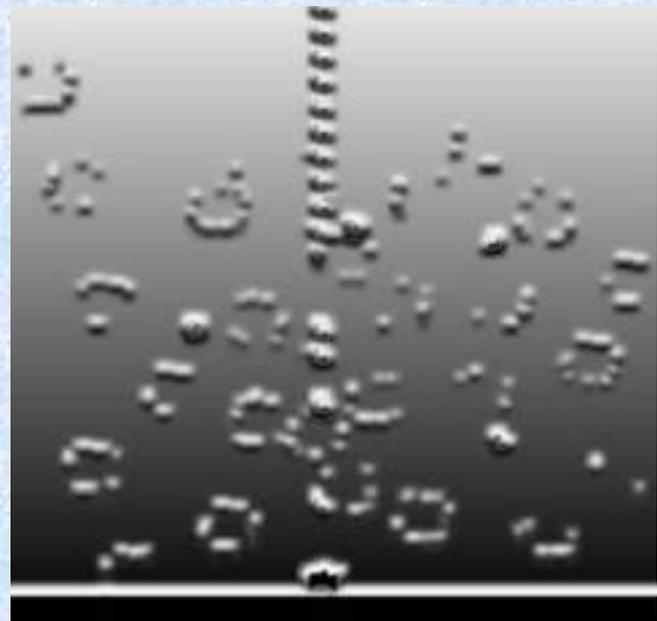


# WHY VACCUUM IS REQUIRED?

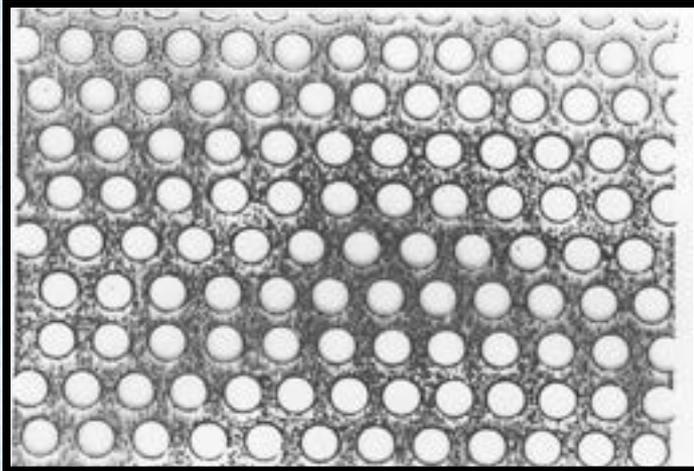


**ELECTRON-BEAM IN A VACUUM**

**ELECTRON BEAM IN AMBIENT AIR**



# PATTERN OF HOLES DRILLED BY EBM



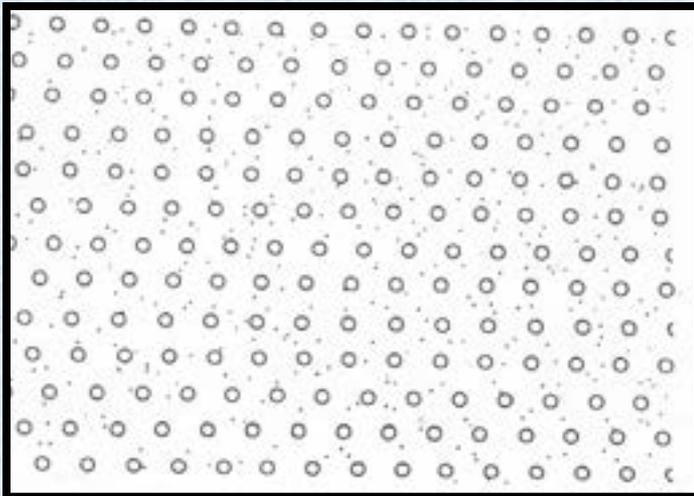
HOLE=0.09 mm $\phi$

HOLES DENSITY = 4000/cm<sup>2</sup>

WORKPIECE- S.S.

THICK = 0.2 mm

TIME = 10  $\mu$ S/HOLE



HOLE  $\phi$  =0.006 mm (6  $\mu$ m)

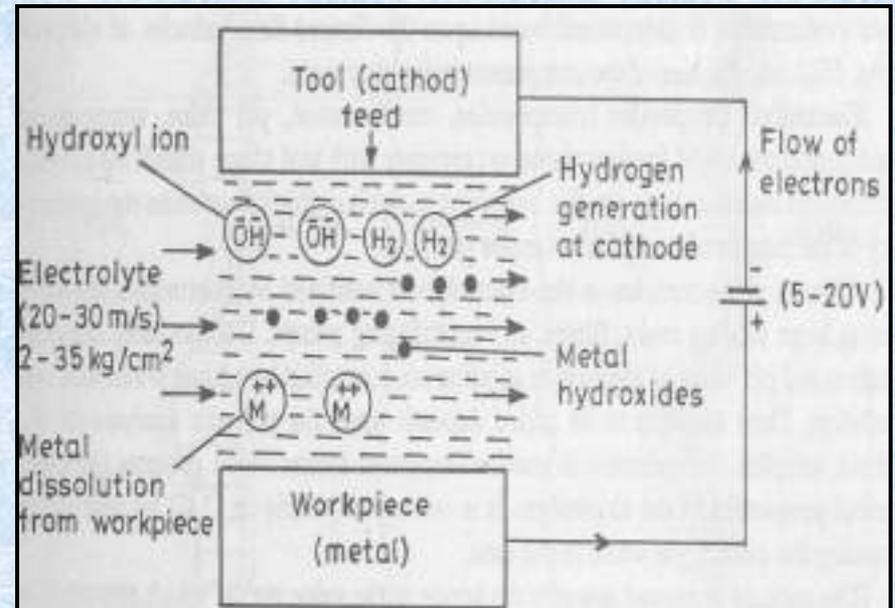
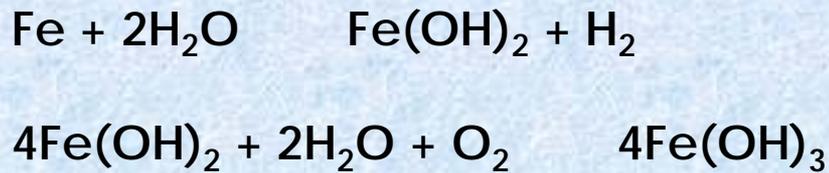
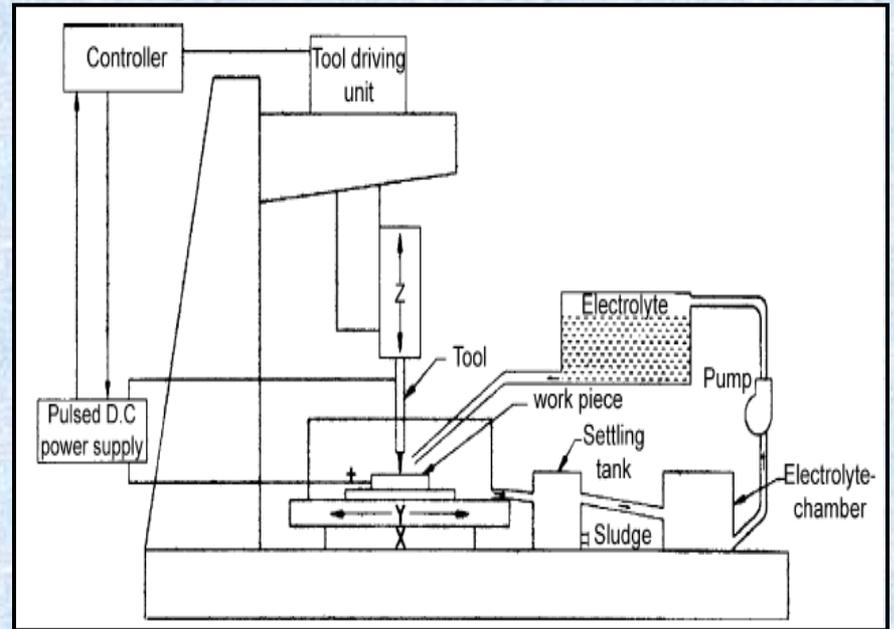
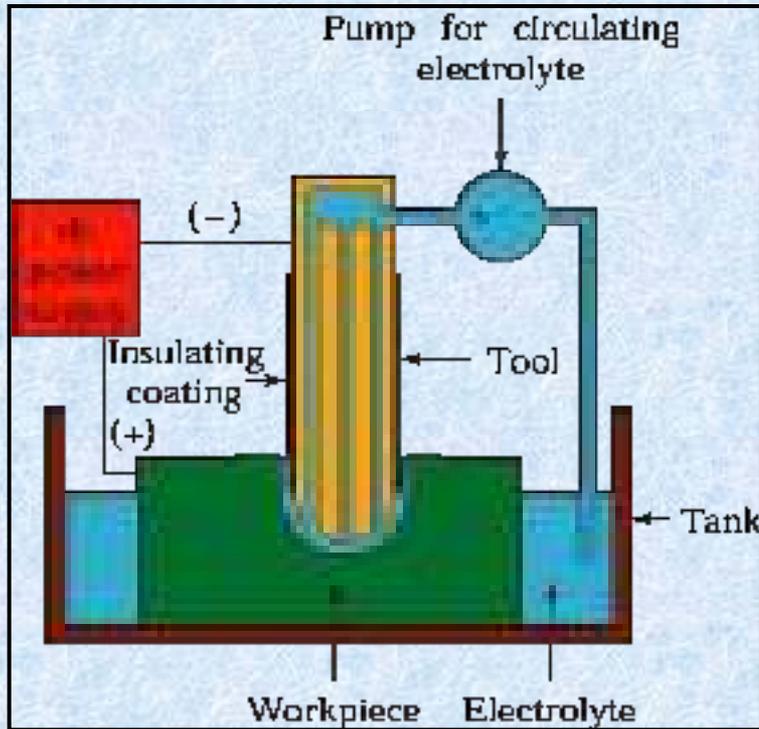
HOLES DENSITY = 200,000 / cm<sup>2</sup>

THICKNESS = 0.12 mm

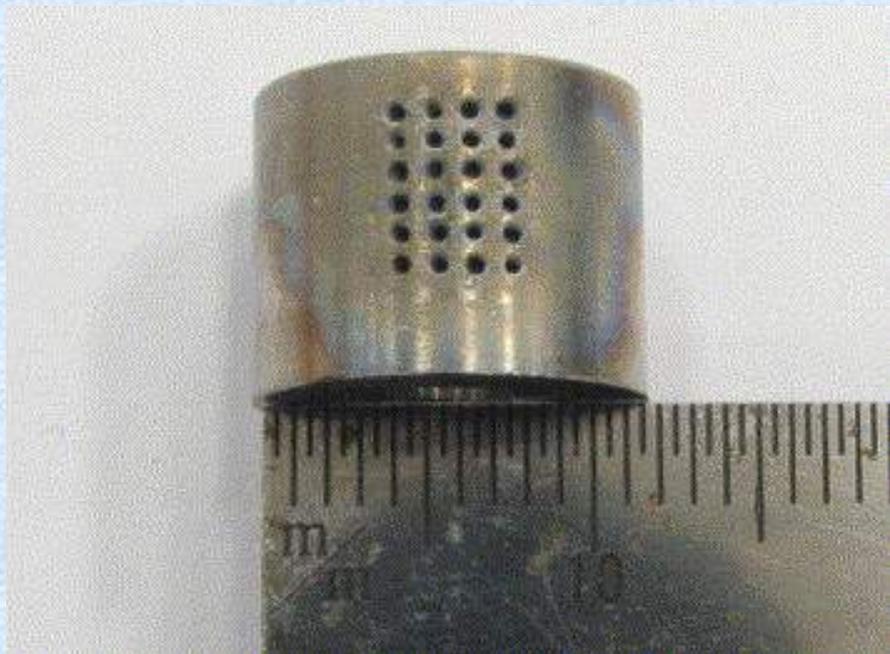
TIME= 2 $\mu$ s / HOLE

# **ELECTRO CHEMICAL MICROMACHINING (ECMM)**

# ELECTRO CHEMICAL MACHINING (ECM)



# APPLICATIONS OF ECMM

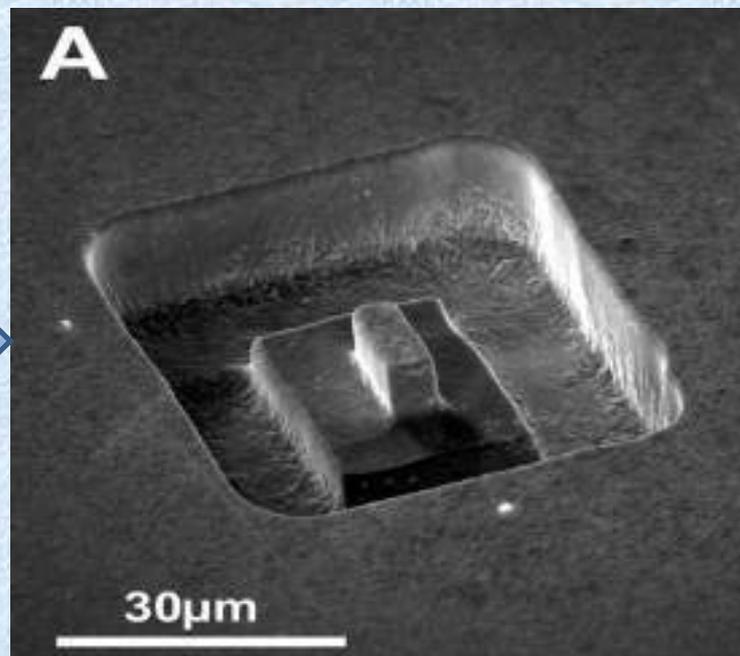


MICRO-HOLES PRODUCED ON A  
Ti<sub>6</sub>Al<sub>4</sub>V CYLINDER USING JET-EMM

PRODUCTION OF HIGH ACCURACY HOLES

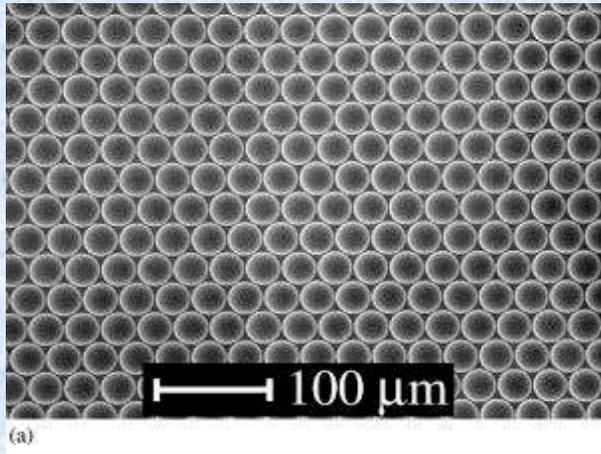
CU STRUCTURE (SMALL PRISM, 5 μm BY  
10 μm BY 12 μm) MACHINED INTO THE  
CU SHEET OF AN ELECTRONIC CIRCUIT  
BOARD

3D MICRO-MACHINING



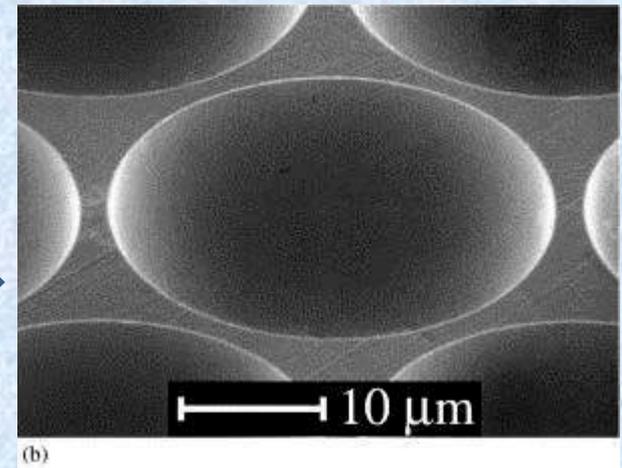
# APPLICATIONS OF ECMM

Titanium surface microstructure  
by through-mask EMM



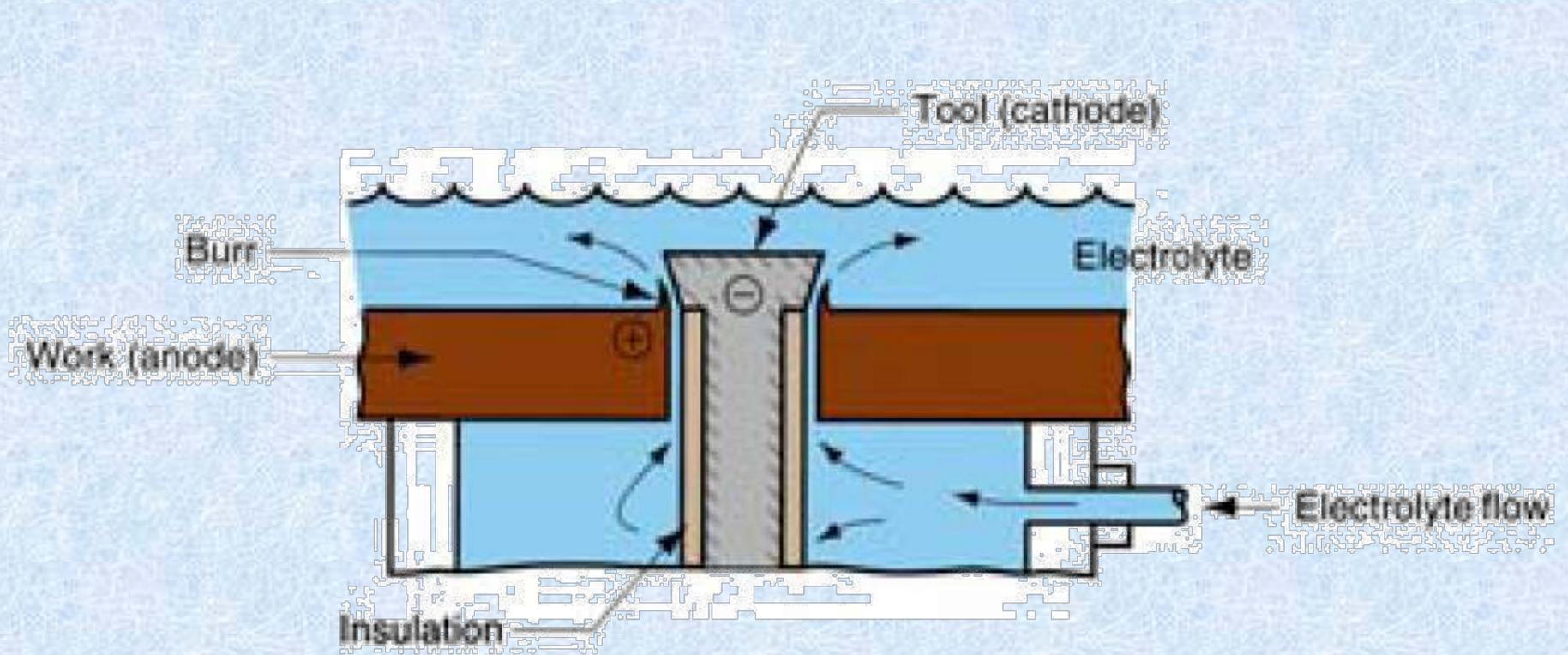
LONG-RANGE ACCURACY AND  
REPRODUCIBILITY OF 30 μm CAVITIES

SMOOTH SURFACE AND SHARP BORDERS THAT  
ARE ACHIEVED UNDER OPTIMIZED DISSOLUTION  
CONDITIONS



# ELECTRO CHEMICAL DEBURRING (ECD)

- Adaptation of ECM to remove burrs or round sharp corners on holes in metal parts produced by conventional through-hole drilling.



# **ION BEAM MICROMACHINING (IBMM)**

# MECHANISM OF ION BEAM MACHINING

- ◆ **SPUTTERING OFF: KNOCKING OUT ATOMS FROM THE WORK-PIECE SURFACE BY THE KINETIC MOMENTUM TRANSFER FROM INCIDENT ION TO THE TARGET ATOMS**
- ◆ **REMOVAL OF ATOMS WILL OCCUR WHEN THE ACTUAL ENERGY TRANSFERRED EXCEEDS THE USUAL BINDING ENERGY.**

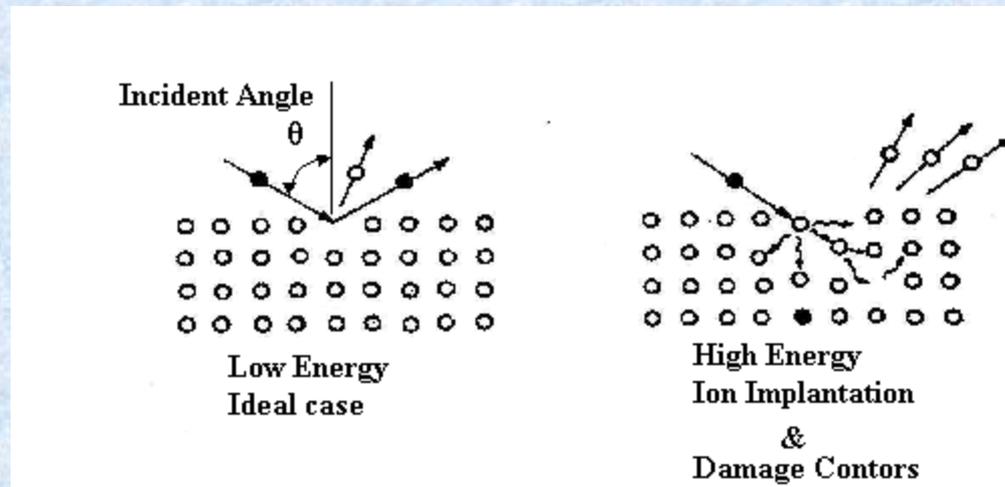
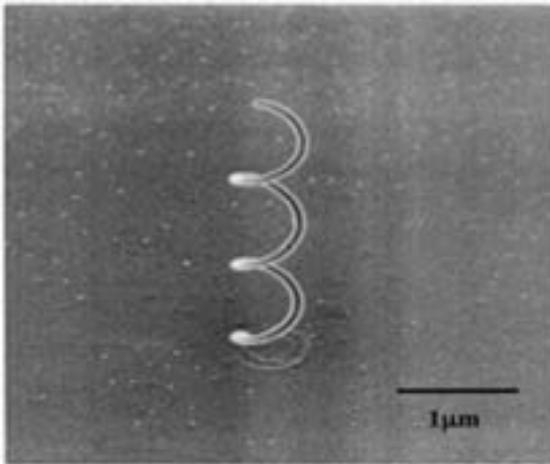


FIG.SCHEMATIC ILLUSTRATION OF THE MECHANISM OF MATERIAL REMOVAL IN IBM

- ◆ **AT SUFFICIENTLY HIGH ENERGY, THE CASCADING EVENTS WILL PENETRATE MORE DEEPLY INTO THE SOLID, SEVERAL ATOMS OR MOLECULES WILL BE EJECTED OUT AND THE BOMBARDING ION WILL BECOME IMPLANTED DEEP WITHIN THE MATERIAL.**

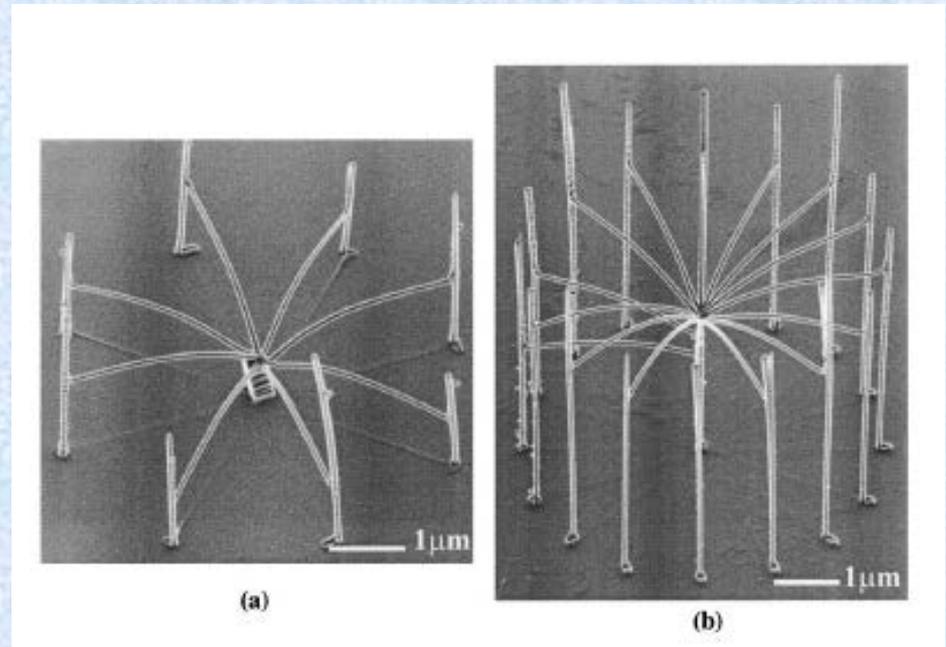


Coil 700 nm pitch, 80 nm line width,  
diamond like amorphous carbon,  
Fabricated by FIB induced deposition



Micro wine glass with 2.75 μm external  
diameter and 12 μm height.

*Shinji Matsui et al, J. Vac. Sci. Technol. B 18(2000) 3181*



(a) Radial DLC free-space-wiring grown into eight  
directions from the center. (b) Radial DLC free-  
space-wiring grown into 16 directions from the  
center.

*T. Morita et al, J. Vac. Sci. Technol. B 21 (2003)*

# TYPICAL MATERIAL REMOVAL RATE IN ION BEAM MACHINING

**TABLE1: REMOVAL RATES BY IBM (SPENCER AND SCHMIDT,1972 [1])**

**DATA : ARGON ION BEAM 60 TO 70° FROM NORMAL  
PRESSURE =  $3 \times 10^{-4}$  TORR**

**VOLTAGE = 6 KV**

**CURRENT = 100  $\mu$ A**

**CURRENT DENSITY = 1 MACM<sup>-2</sup> OVER 1 CM DIAMETER AREA**

<b>MATERIAL</b>	<b>REMOVAL (MILLING) RATE, (<math>\mu</math>M HR<sup>-1</sup>)</b>
<b>QUARTZ</b>	<b>2</b>
<b>GARNET</b>	<b>1</b>
<b>CERAMIC</b>	<b>1</b>
<b>GLASS</b>	<b>1</b>
<b>GOLD</b>	<b>2</b>
<b>SILVER</b>	<b>3</b>
<b>PHOTO RESIST MATERIAL (KTFR)</b>	<b>1</b>
<b>PERMALLOY</b>	<b>1</b>
<b>DIAMOND</b>	<b>1</b>

# NANOFINISHING PROCESSES: AN OVERVIEW



## Micro / nano finishing

### Traditional

Grinding

Lapping

Honing



SHAPE AND SIZE CONSTRAINTS  
WITH EACH OF THESE  
TRADITIONAL FINISHING PROCESSES

### Advanced

AFM

MAF

MRF

CMP

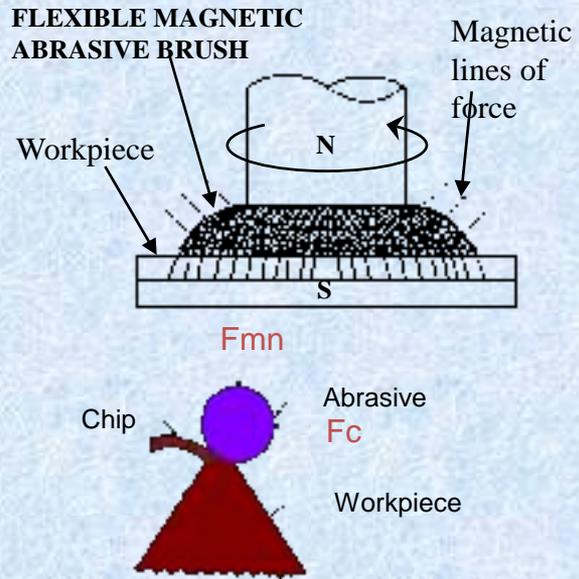
MRAFF

ELID

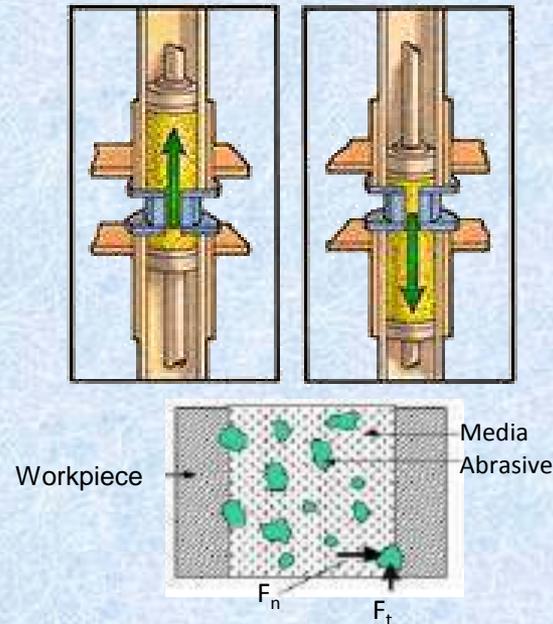
MFP

CMMRF

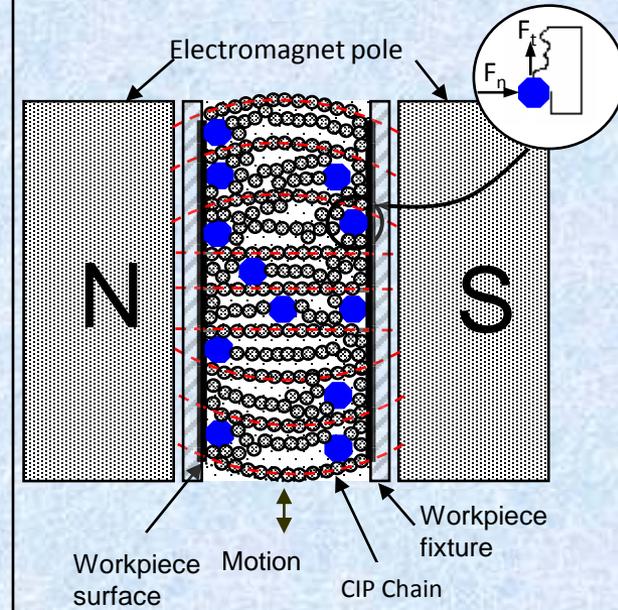
# MAF



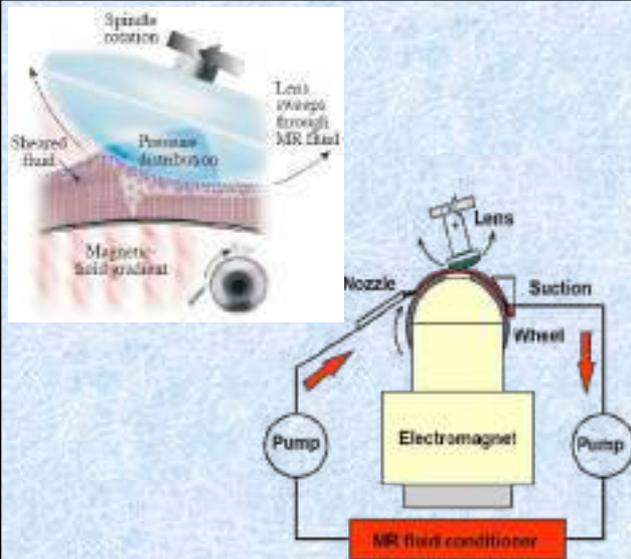
# AFM



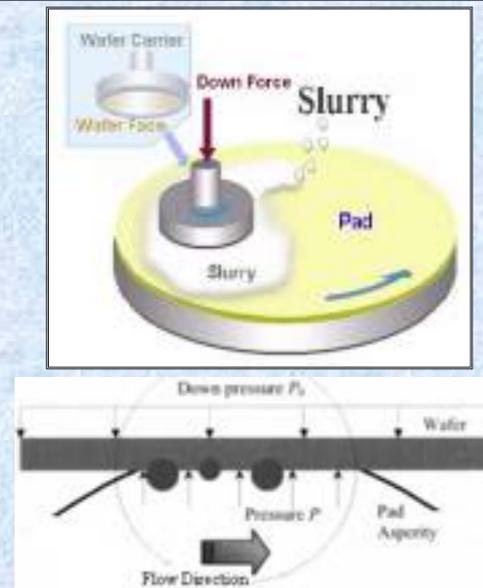
# MRAFF



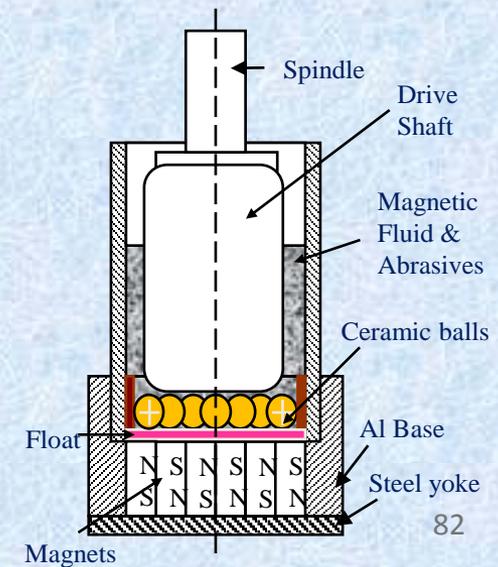
# MRF



# CMP



# MFP





**OVERVIEW OF  
ADVANCED ABRASIVE FINISHING  
PROCESSES**

# WHY ADVANCED ABRASIVE FINISHING PROCESSES?

Complex Geometrical Shapes.

Labor Intensive Nature of Traditional Finishing Operations.

Difficulties in Controlling Abrading Forces.

Nano-meter ( $10^{-9}$  m) Surface Finish Requirements.

# ADVANCED ABRASIVE FINISHING PROCESSES

**MAF**      **Magnetic Abrasive Finishing**

**AFF**      **Abrasive Flow Finishing**

**MRAFF**      **Magnetorheological Abrasive Flow Finishing**

**MRF**      **Magneto Rheological Finishing**

**CMP**      **Chemo Mechanical Polishing**

**MFP**      **Magnetic Float Polishing**

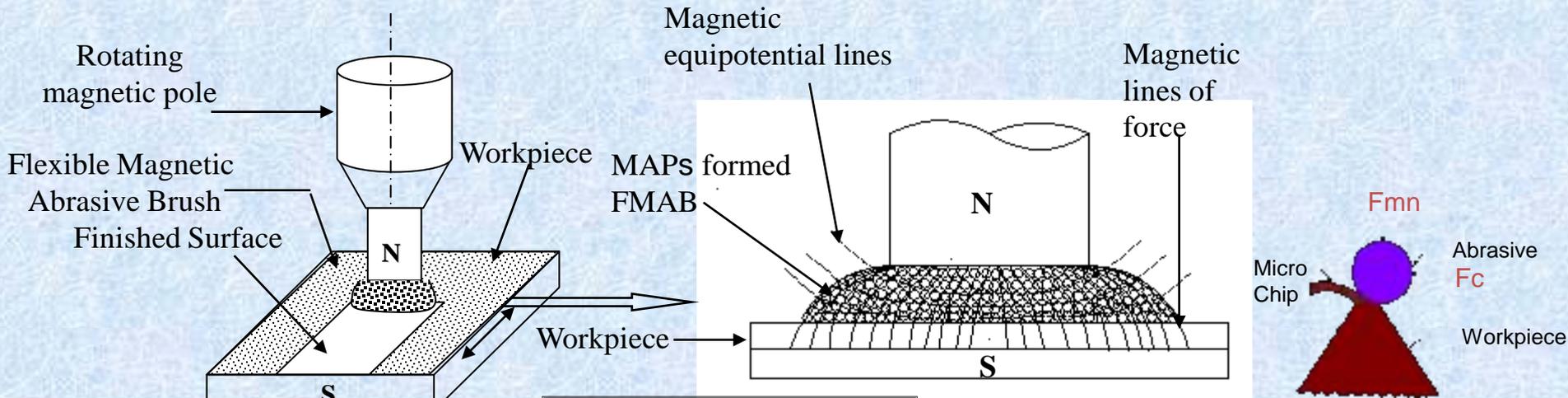
IN ALL THESE PROCESSES **NORMAL FORCE** IS RESPONSIBLE FOR PENETRATION OF ABRASIVE INTO WORKPIECE AND **SHEAR FORCE** TO REMOVE THE MATERIAL IN THE FORM OF **MICROCHIP**

# **MAGNETIC ABRASIVE FINISHING (MAF)**

# SCHEMATIC VIEW OF MAF WORKING PRINCIPLE

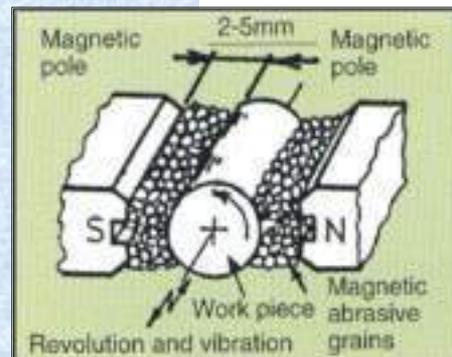
WORKING GAP → FILLED WITH MAPs → FORMS FMAB

↓  
MULTIPOINT CUTTING TOOL



## SALIENT FEATURES

Ra = AS GOOD AS 8 nm



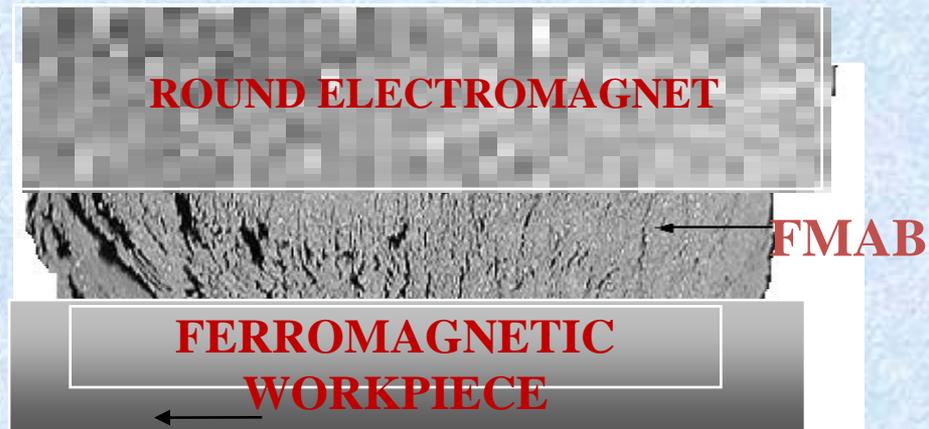
# MAGNETIC ABRASIVE FINISHING (MAF) (DST SPONSORED PROJECT)

## EXPERIMENTAL SET-UP



DESIGNED AND FABRICATED AT IITK

## DIGITAL PHOTOGRAPH OF FLEXIBLE MAGNETIC ABRASIVE BRUSH (FMAB)

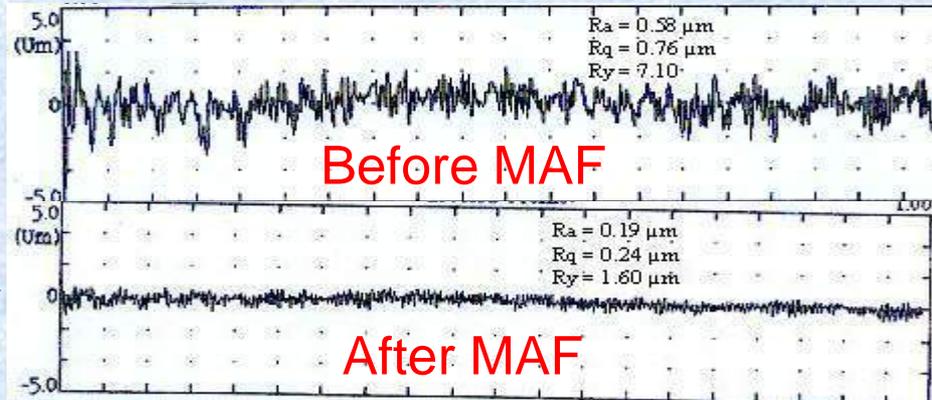


# EXPERIMENTAL RESULTS OF MAF

## Surface Profilometer Results

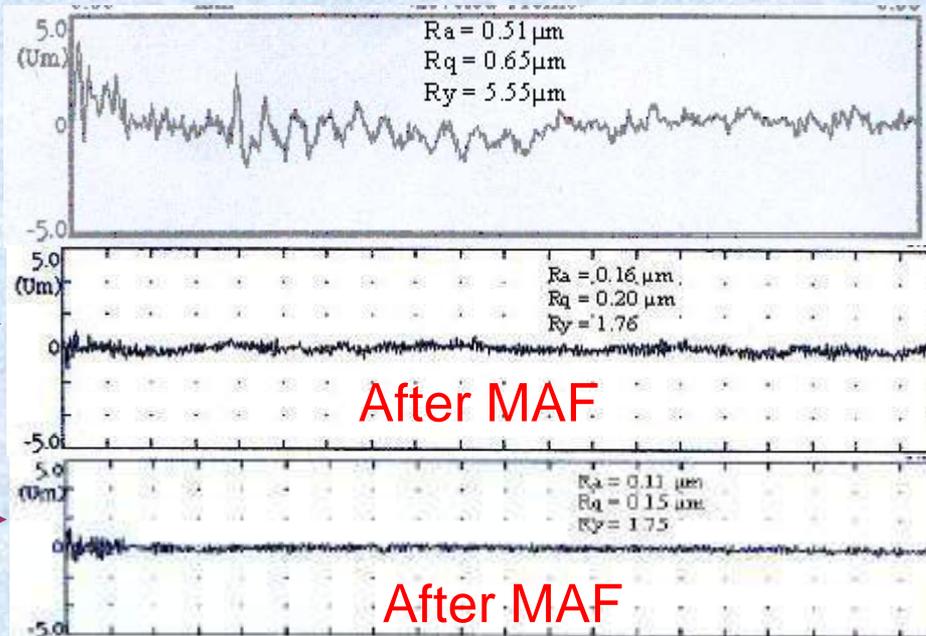
### DC-MAF

$I=0.88$  A,  
 $G=500$   
 $N=11$  →  
(No. of cycles)



Before MAF

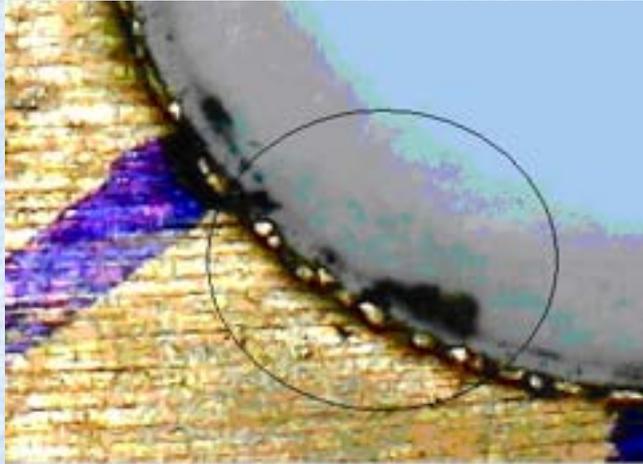
$I=0.75$  A,  
 $G=600$  →  
 $N=9$



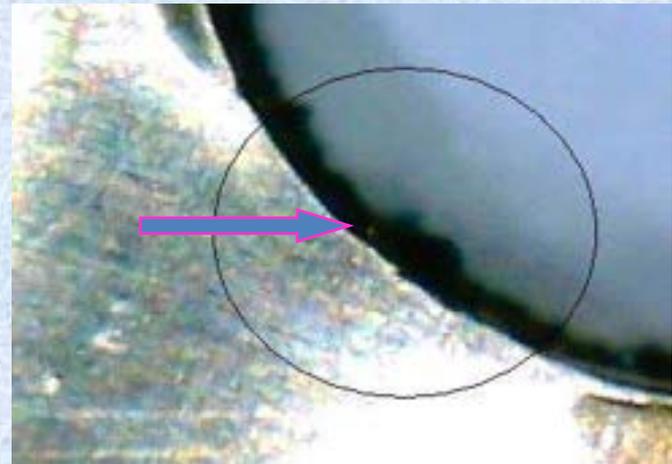
$I=0.75$  A,  
 $G=800$  →  
 $N=9$

BEST SURFACE ROUGHNESS ACHIEVED WAS 40nm

# MICRO DEBURRING APPLICATION OF MAF



**(a)**



**(b)**

Drilled hole edge (a) before, (b) after deburring

# **ABRASIVE FLOW FINISHING (AFF)**

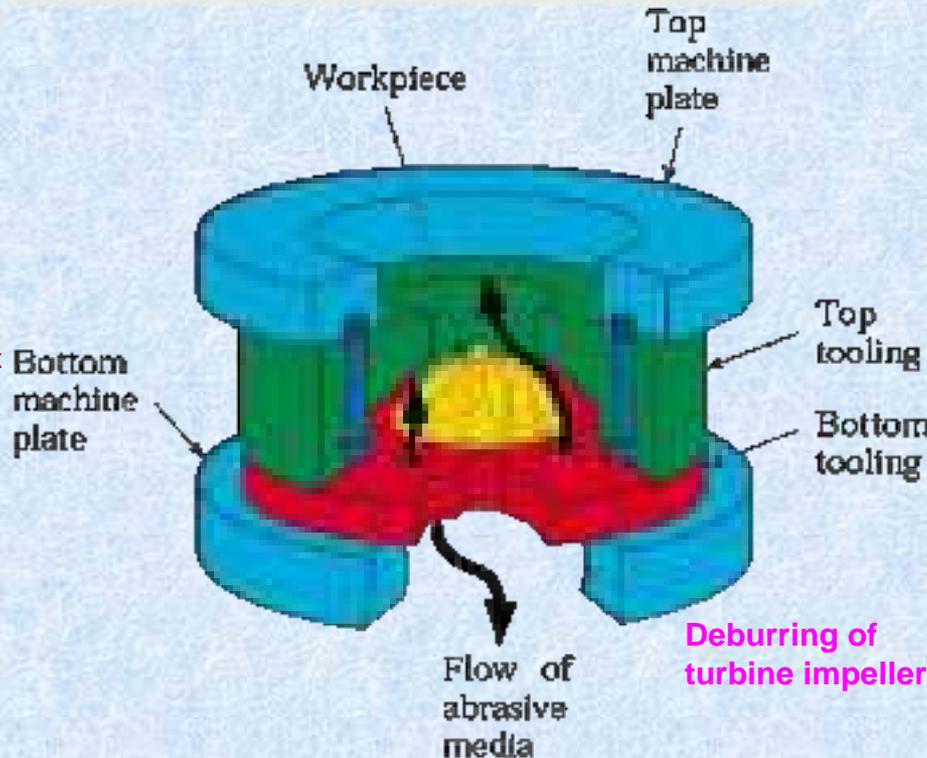
# ABRASIVE FLOW MACHINING (AFM)

- Two vertically opposed cylinders extrude abrasive laden medium back & forth through passage formed by the workpiece & tooling

- **Medium** : Visco-elastic Polymer with special rheological properties

+

Fine Abrasive Particles

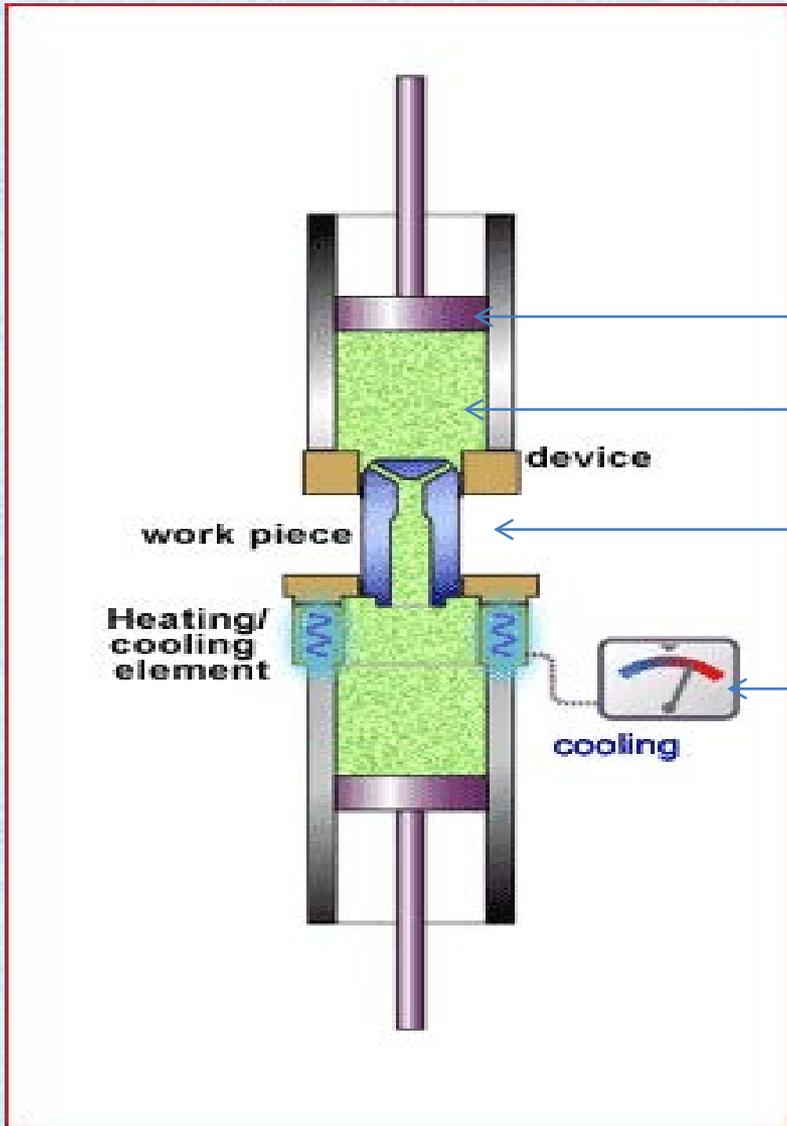


Abrasive Flow Machining (AFM) at IIT - K  
(DST SPONSORED PROJECT)



Photograph Showing AFM set-up

**Fig: Abrasive flow finishing setup for knee joint finishing**



Piston

Silly Putty (viscoelastic) + SiC  
(abrasive)

Workpiece held in fixture

Thermostat for temp control

work piece

device

Heating/  
cooling  
element

cooling

# KEY FEATURES OF AFM

**VERSATILITY – FINISH COMPLEX SURFACES OF VARIOUS SIZES.**

◆ **SURFACE FINISH -  $0.1 \mu\text{m}$  to  $0.05 \mu\text{m}$   $R_a$ .**

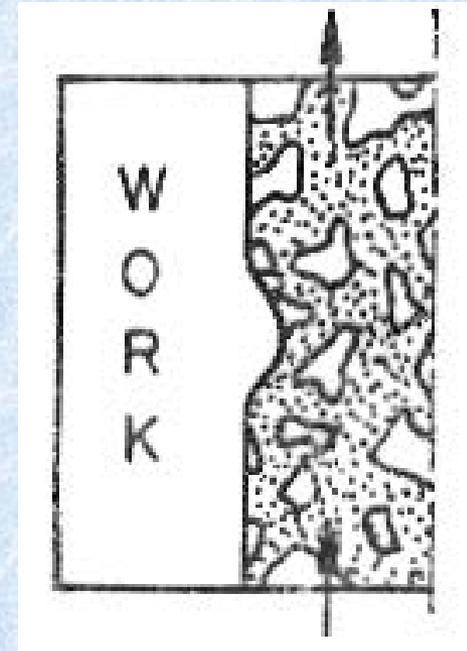
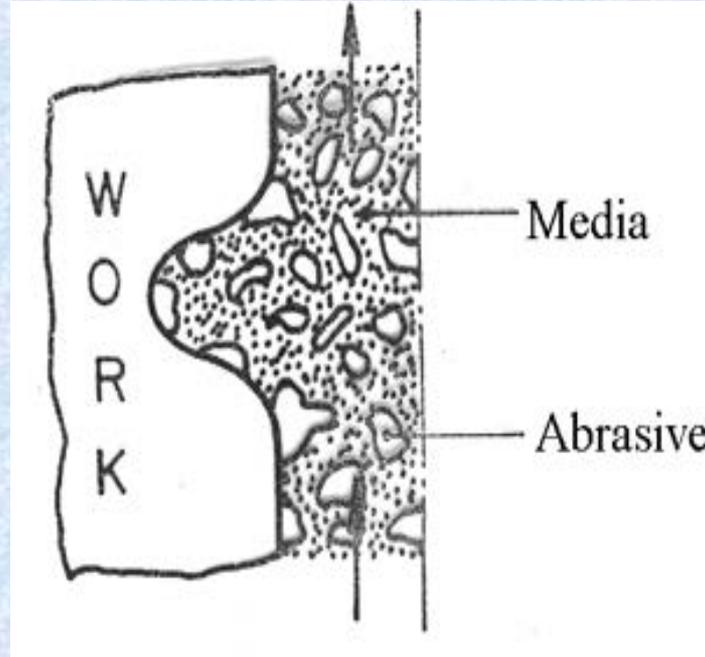
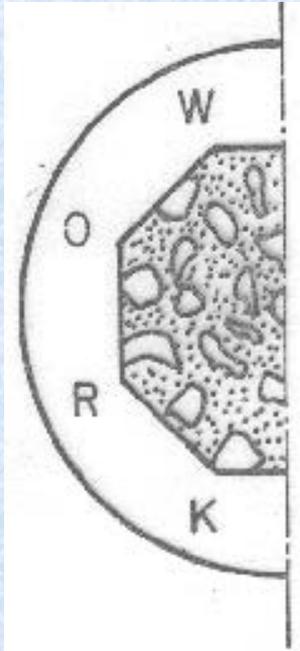
**FORCE :  $0.0009\text{N}$  --  $0.002\text{N}$  Per Particle**

**DEPTH OF PENETRATION :  $5\text{nm}$  --  $30\text{nm}$**

## LIMITATIONS:

- ◆ **VISCOELASTIC POLYMERIC MEDIUM – COSTLY AND LACK OF AVAILABILITY.**
- ◆ **MEDIUM RHEOLOGICAL PROPERTIES – VARY IN UNCONTROLLED MANNER DURING PROCESS.**
- ◆ **LACK OF DETERMINISM.**

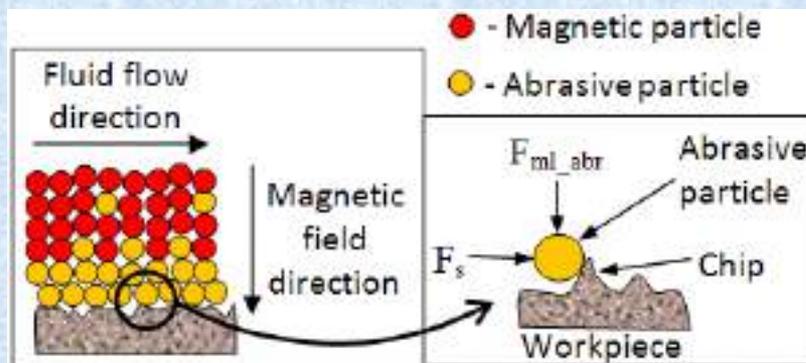
# AFM MEDIA ACTS AS A *SELF-DEFORMABLE STONE*



**MAGNETORHEOLOGICAL  
FINISHING  
(MRF)**

# MRF- Mechanism of material removal

- CI particles form a chain-like columnar structure, with the application of magnetic field and they are aligned along the lines of magnetic force.
- The magnetic force between iron particles provides bonding strength to it.
- When these chains have relative motion with respect to the workpiece surface the asperities on the surface are abraded due to shearing / plastic deformation at the tips.



# MAGNETORHEOLOGICAL FINISHING (MRF)

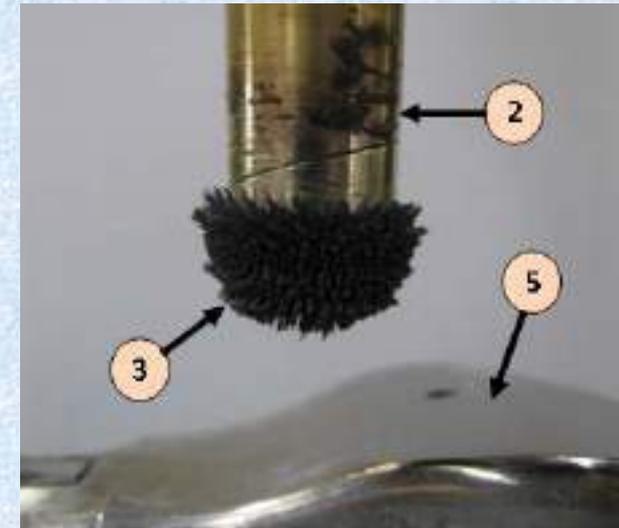
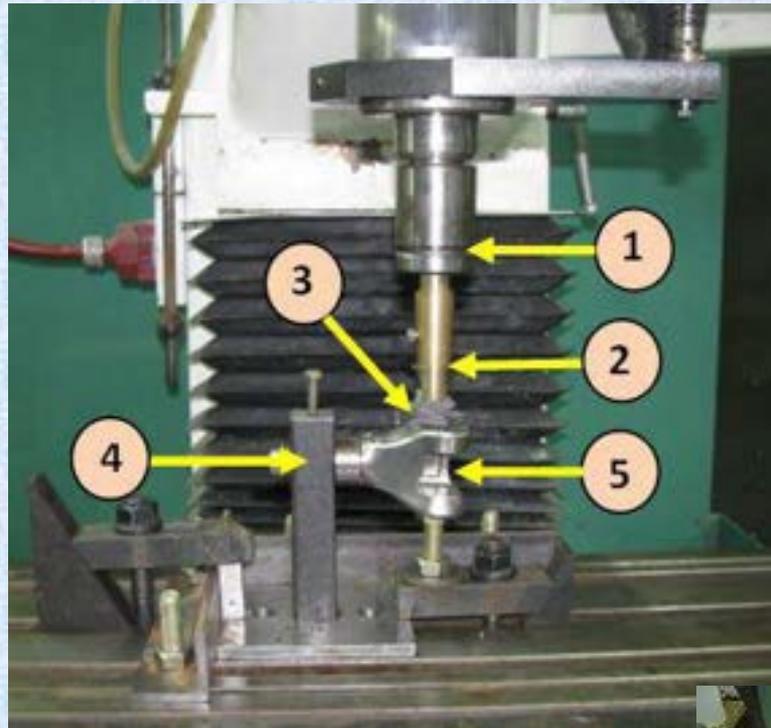
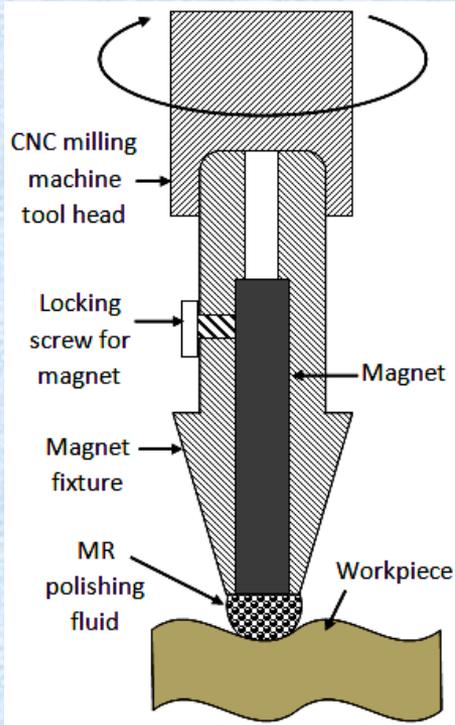
- Fluid is extruded onto a rotating wheel in a **thin ribbon** that contacts the optical / WORKPIECE surface.
- **Electromagnet** below the polishing wheel exerts a strong local **Magnetic field gradient**.
- Precisely controlled zone of **magnetized fluid** becomes the **Polishing tool**.

MR-fluids are suspension of ferromagnetic particles in water/oil that reversibly stiffens under the influence of magnetic field.

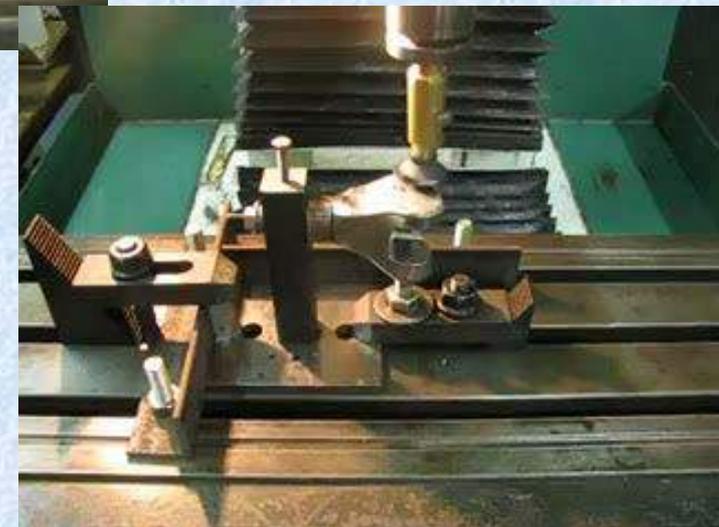
**Stiffness of the fluid  $\propto$  Magnetic Field Strength.**



# Apparatus and tooling for freeform surface

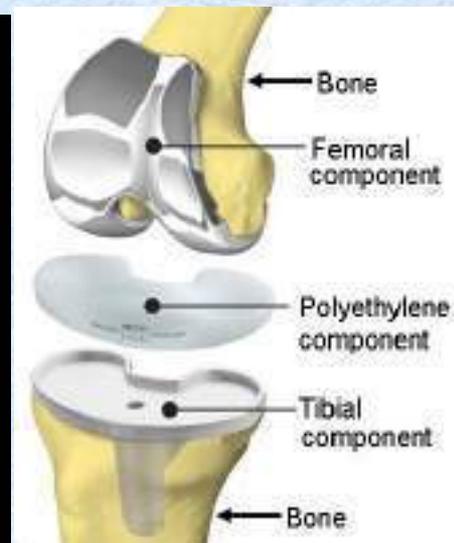


(1- CNC milling M/c head, 2- MR finishing tool, 3- MR polishing fluid, 4- fixture for knee joint implant (Ti6Al4V), 5- knee joint implant)



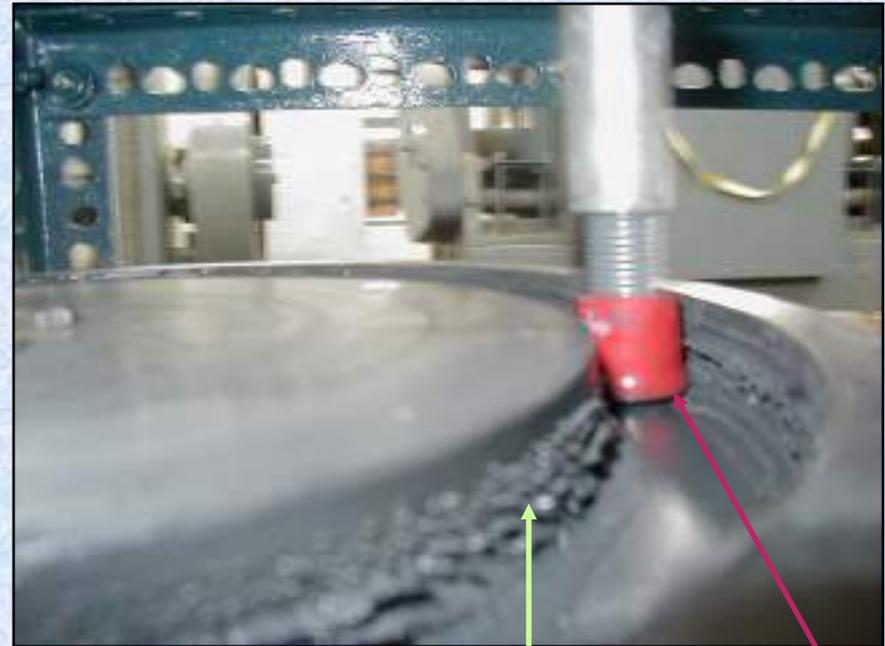
# Finishing of freeform surface

- Knee joint implants consist of metal femoral and tibial components with a plastic polyethylene insert sandwiched between to restore joint function.
- Surface roughness of knee joint implant has a significant effect on the force at the connection and reaction of tissues in the joint area and behaviour of germs in bone tissue (Mathia et al., 2011).
- **Wear by abrasion** is one of the main causes for **failures of knee joints** because over time, the continuous movement between the metal and plastic can cause the polyethylene to crack, pit and delaminate.
- It may also cause microscopic particles to break off which in turn attack the body's immune system.



# MRF EXPERIMENTAL SETUP AT IIT - K

(BY B. TECH. STUDENTS PROJECT)

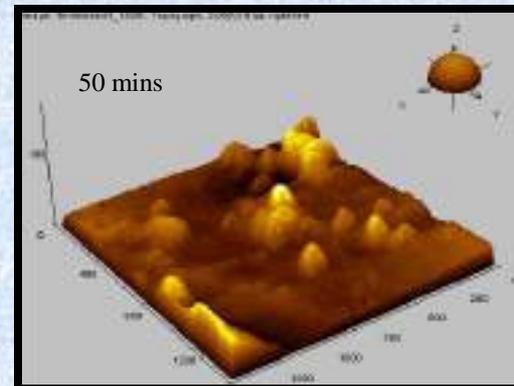
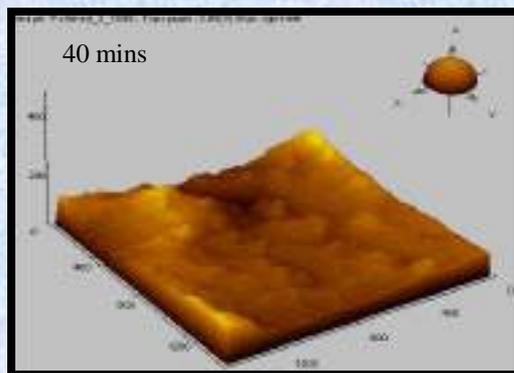
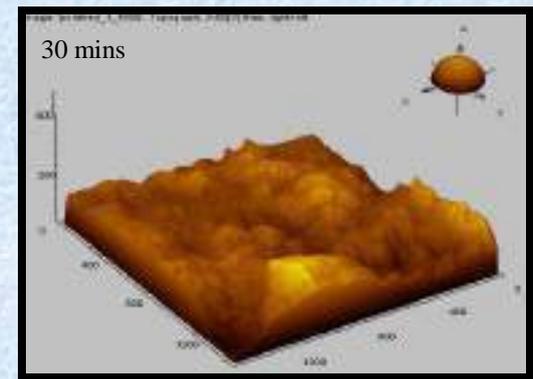
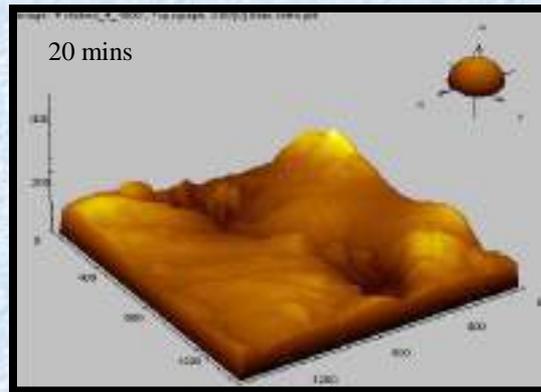
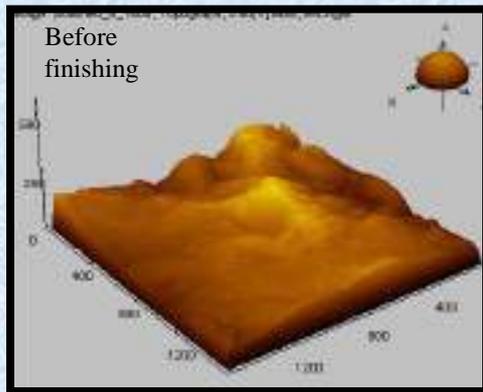


MR FLUID

WORKPIECE / LENS

# EXPERIMENTAL RESULTS OF MRF

**53 nm (RMS)**

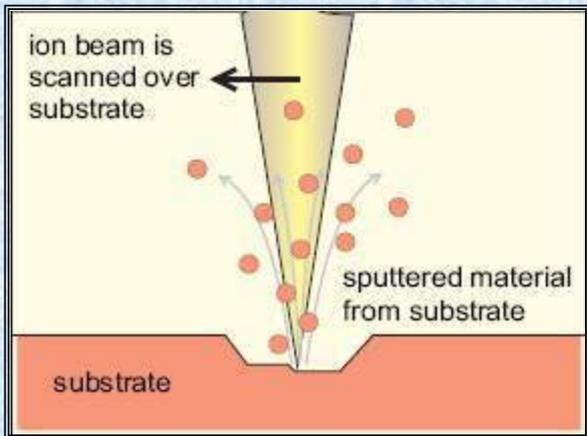
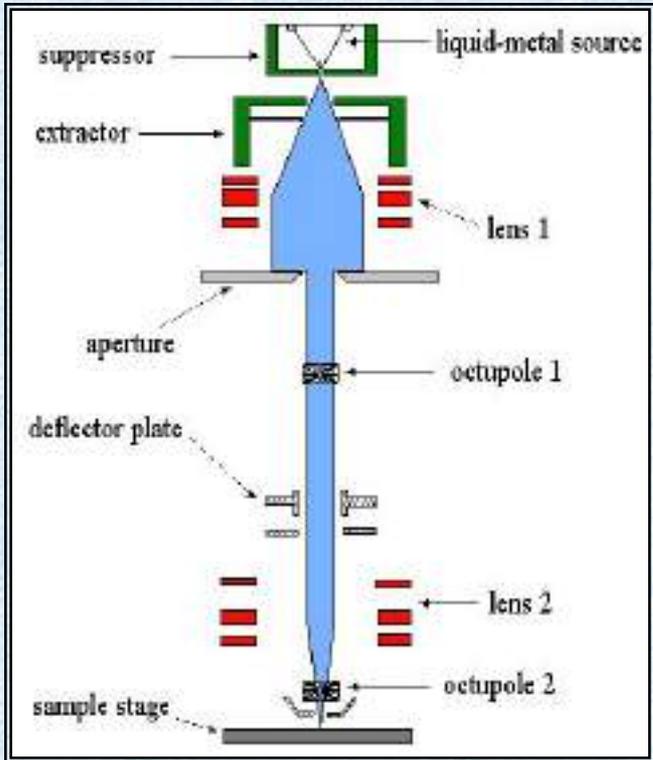


**11 nm (RMS)**

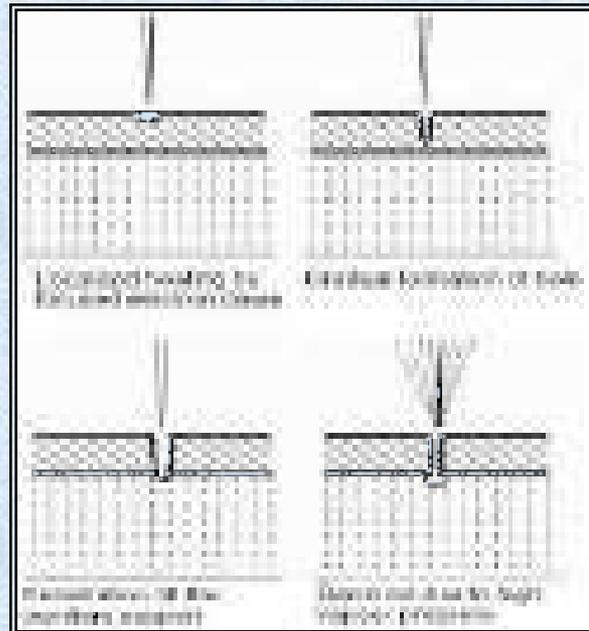
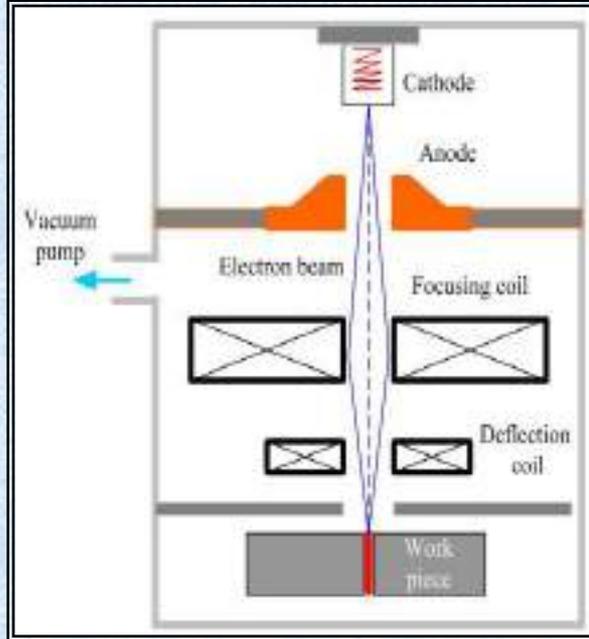
**THANK YOU**



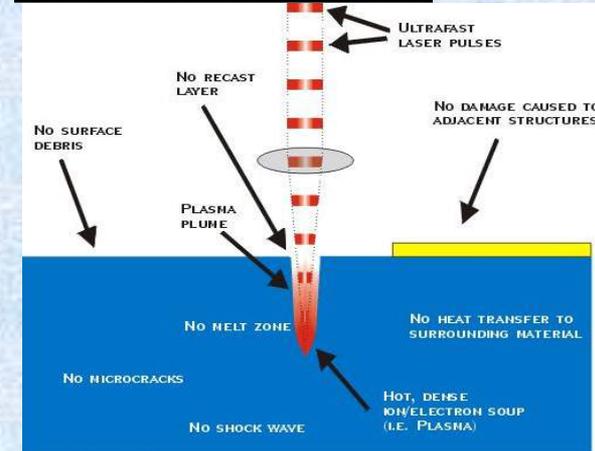
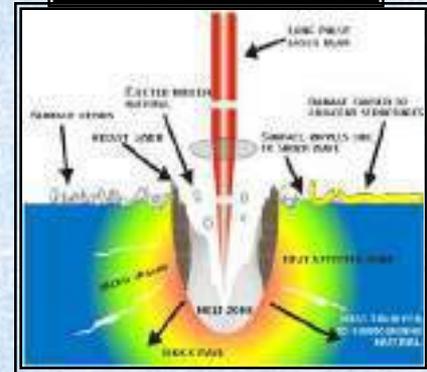
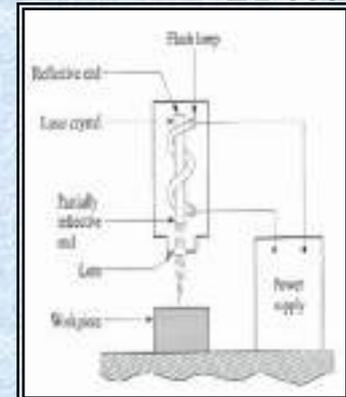
# IBM



# EBM



# LBM



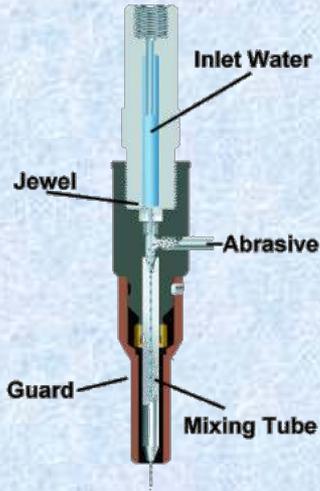
**SHORT PULSE LASER MACHINING**

Ref.: Cmxr lasers industry,

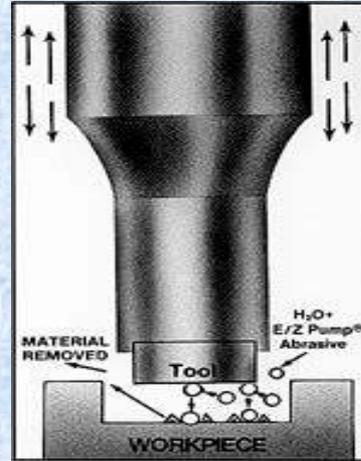
[www.cmxr.com/industrial/handbook/](http://www.cmxr.com/industrial/handbook/)

# MECHANISM OF MATERIAL REMOVAL IN MECHANICAL MICROMACHINING

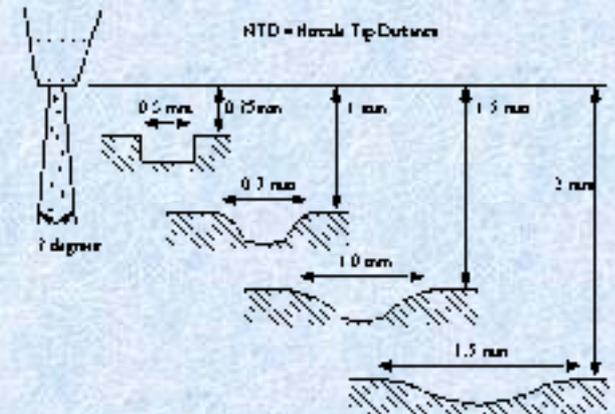
## ABRASIVE WATER JET MACHINING



## ULTRASONIC MACHINING

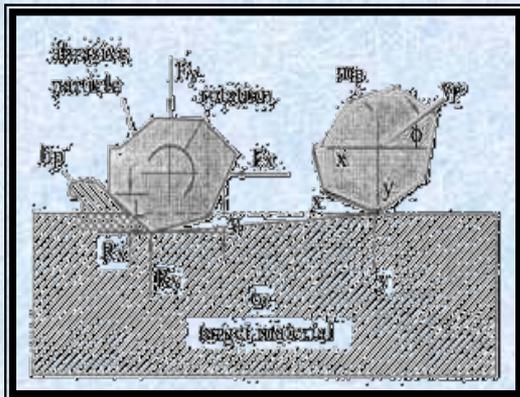


## ABRASIVE JET MACHINING

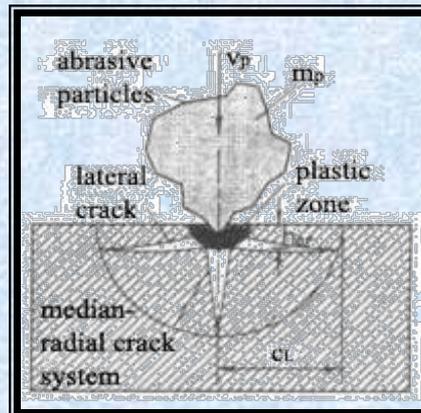


## AWJM, AJM, USM

### Mechanism of material removal in ductile material

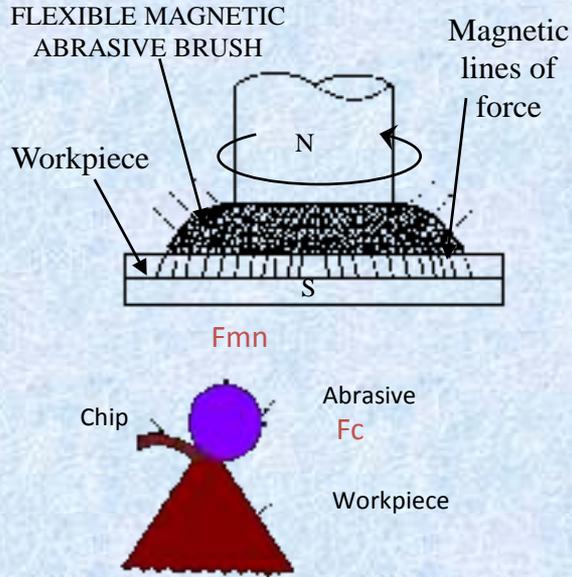


### Mechanism of material removal in brittle material

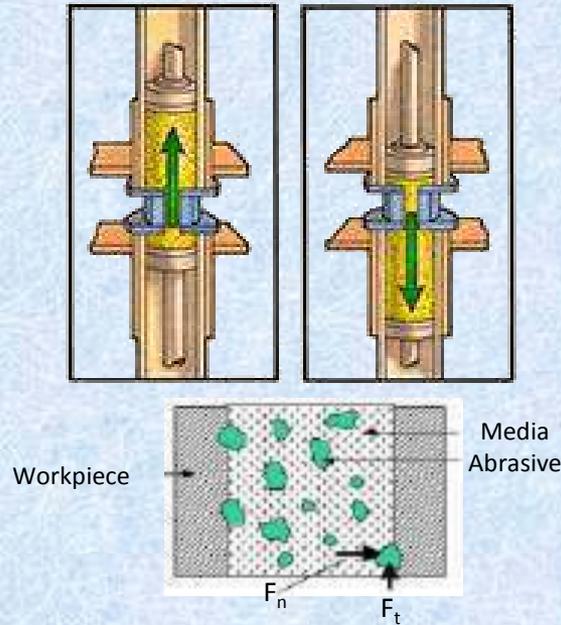


**FORCES ACTING ON EACH PARTICLE AND PARTICLE SIZE WILL DEC IDE THE SCALE OF MATERIAL REMOVED :  
MACRO, MICRO, NANO**

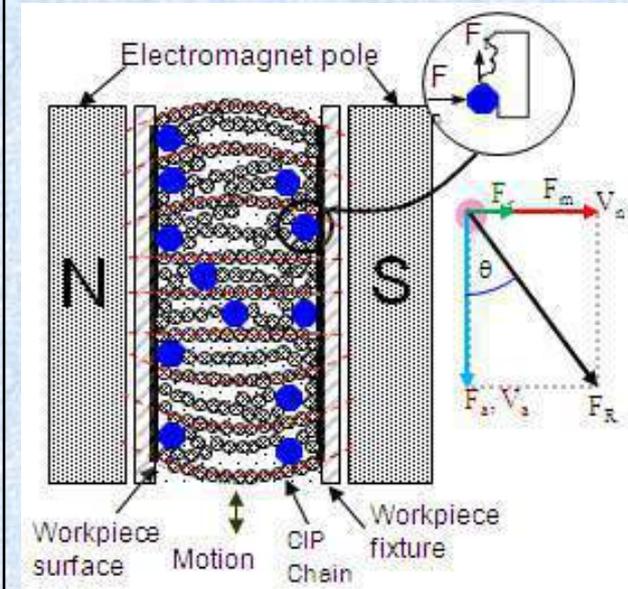
# MAF



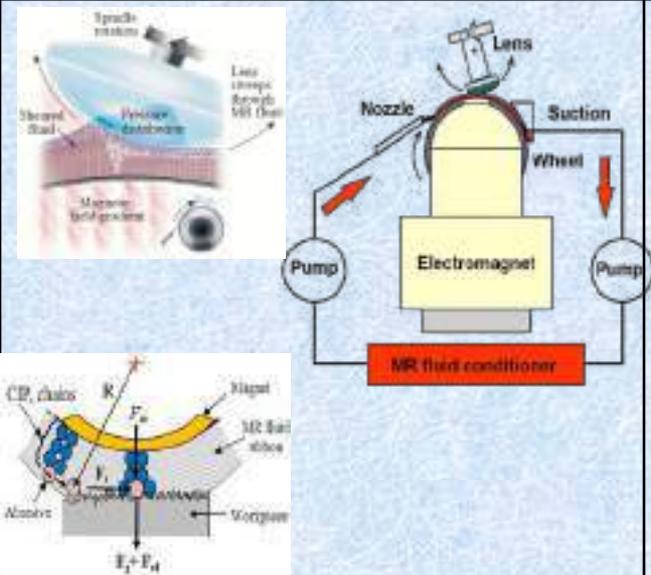
# AFM



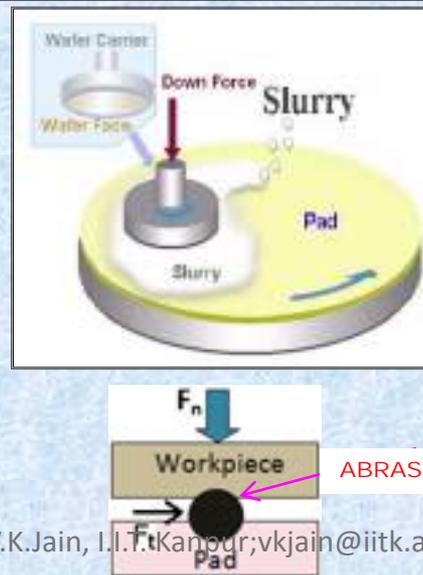
# MRAFF



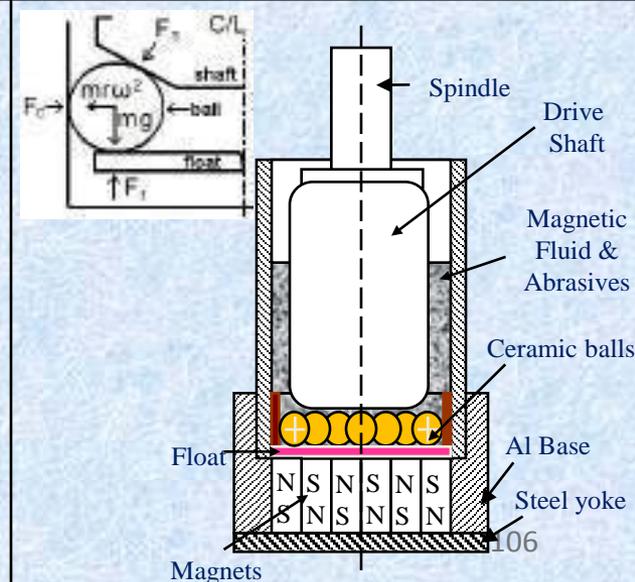
# MRF



# CMP



# MFP



# ADVANCED MACHINING PROCESSES



## Questions bank for “introduction to AMPs”

- Q.1 Name the important factors that should be considered during the selection of an Advanced Machining Process for a given job.
- Q.2 Classify the different types of Advanced Machining Processes based on different criteria.
- Q.3 What do you understand by the term “Micromachining”? Classify the different types of micromachining methods. Also write down the ranges of macro, meso, micro, and Nano machining.
- Q.4 What do you understand by “hybrid process”? List out the names of hybrid processes and the advantages of a hybrid process over its constituent processes.
- Q.5 Classify the advanced machining processes based on electrical properties of materials.
- Q.6 what is the mechanism of material removal in Laser beam machining?
- Q.7 Differentiate between chemical and electrochemical machining processes.
- Q.8 Write the element of EBM.
- Q.9 what do you understand by a finishing process?
- Q.10 what are the constraints that limit the performance of different kinds of AMPs
- Q.11 what do you understand by the word “unconventional” in unconventional machining processes ? Is it justified to use this word in the context of the present day medium and large scale engineering industries?
- Q.12 Classify the advanced machining processes on the basis of type of the energy employed.
- Q.13 What are the advanced machining processes which can be used for magnetic material?

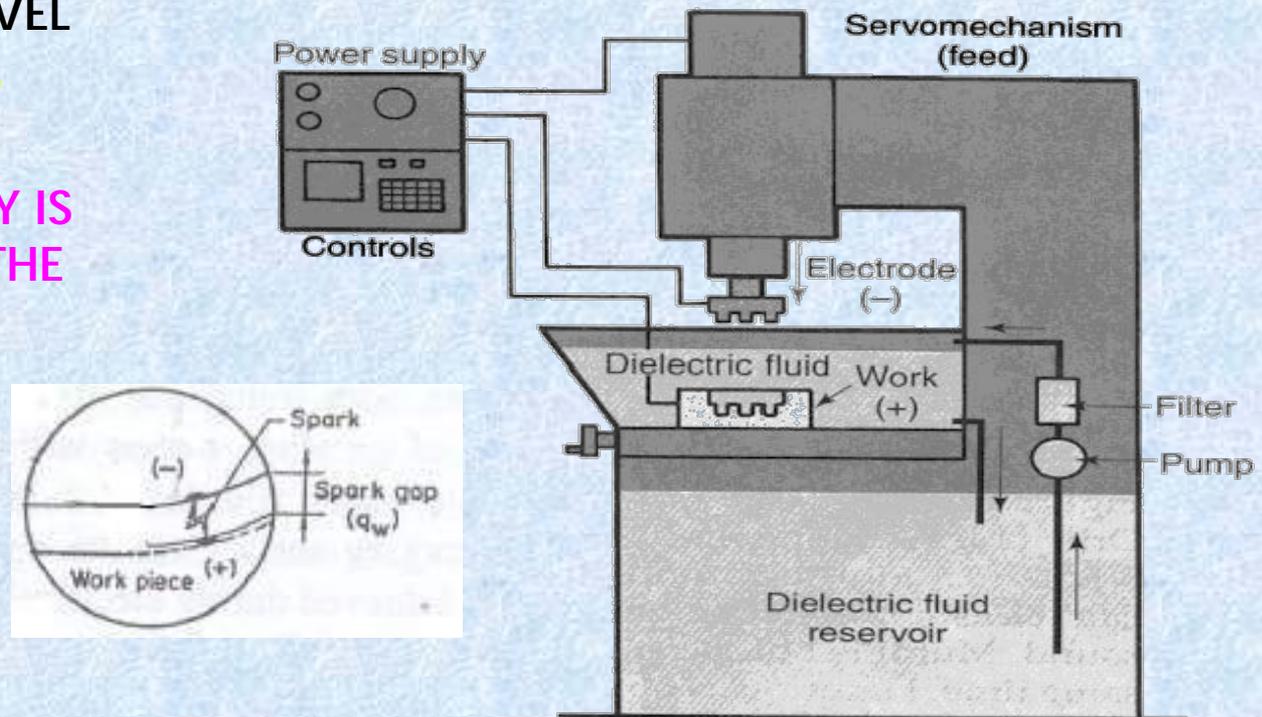
# BASICS OF EDMM

- IN EDM MATERIAL IS REMOVED BY THE **THERMAL EROSIVE ACTION** OF ELECTRICAL DISCHARGES (SPARKS) PROVIDED BY THE OF A PULSE GENERATOR.

• THE SAME PRINCIPLE OF EDM IS APPLIED TO REMOVE MATERIAL AT MICRON LEVEL FOR **MICROMACHINING**.

• IN MICRO-EDM, THE KEY IS TO LIMIT THE ENERGY IN THE DISCHARGE (SPARK)

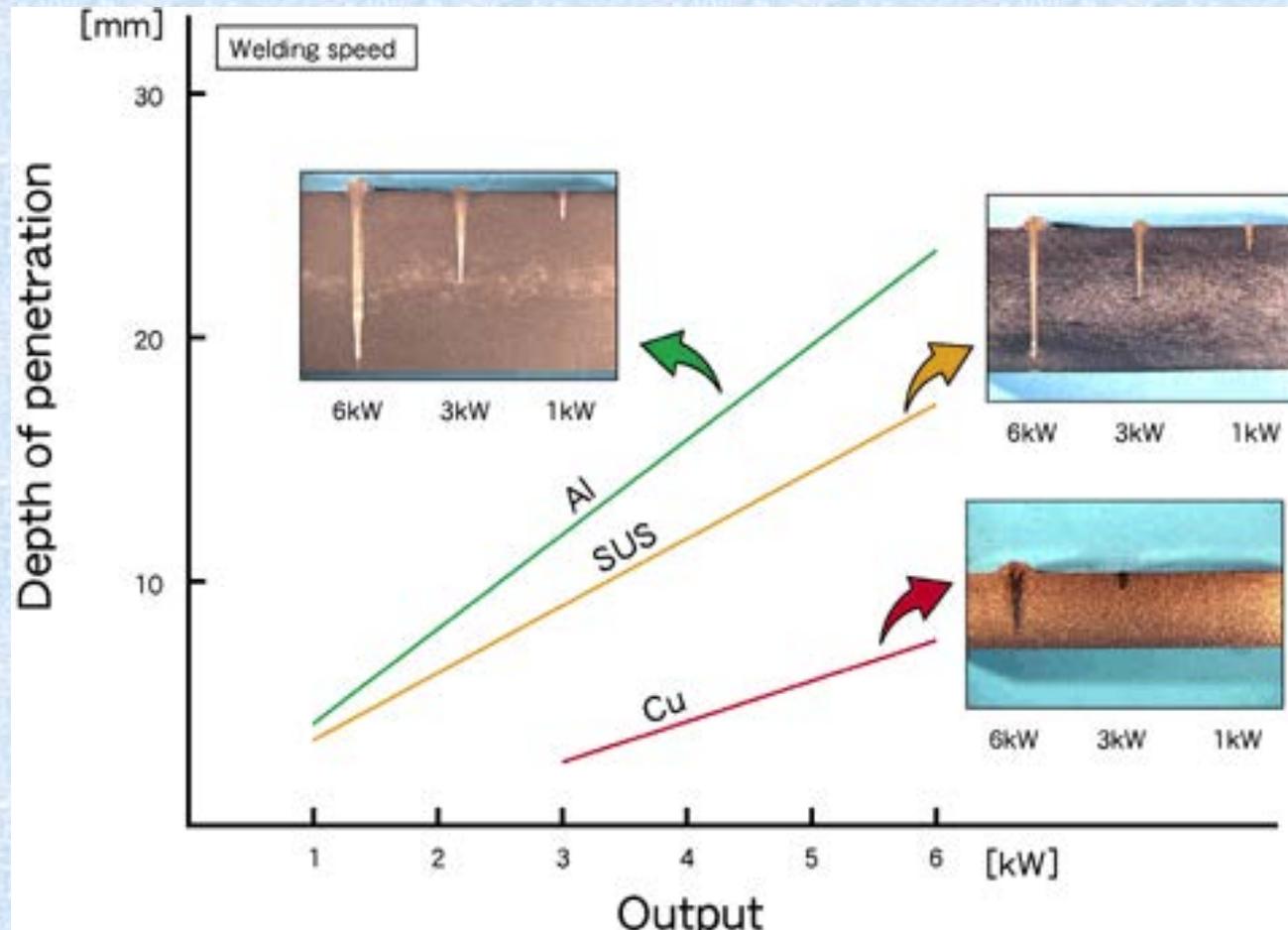
Diagram of EDM process



# PROCESS CHARACTERISTICS

PROPERTY	VALUE
<b>MECHANISM OF MATERIAL REMOVAL</b>	MELTING, VAPORIZATION
<b>MEDIUM</b>	VACUUM
<b>TOOL</b>	BEAM OF ELECTRON MOVING AT VERY HIGH SPEED
<b>MAX. MRR</b>	10 mm <sup>3</sup> /min (MAY BE IN SPECIAL CONDITIONS)
<b>SPECIFIC POWER CONSUMPTION</b>	450 W/mm <sup>3</sup> -min
<b>CRITICAL PARAMETERS</b>	ACCELERATING VOLTAGE, BEAM CURRENT, BEAM DIA., WORK SPEED, MELTING TEMPERATURE
<b>MATERIALS APPLICATION</b>	ALL MATERIALS (CONDUCTIN & NON-CONDUCTING BOTH)
<b>SHAPE APPLICATION</b>	DRILLING FINE HOLES, CUTTING CONTOURS IN SHEETS, CUTTING NARROW SLOTS
<b>LIMITATIONS</b>	VERY HIGH SPECIFIC ENERGY CONSUMPTION, NECESSITY OF VACUUM, EXPENSIVE MACHINE

# E-BEAM WELDING



SUS →> SULPHUR STEEL

# Micro / nano finishing

**traditional**

**Grinding**

**Lapping**

**Honing**

**Advanced**

**AFM**

**MAF**

**MRF**

**CMP**

**MRAFF**

**ELID**

**MFP**